



Choosing the Ideal UIS2 Optics Components for Your Equipment



UIS2

World-leading optics

The wide range of Olympus components introduced here allows users in such diverse fields as research, inspection and production to take advantage of the quality, flexibility and outstanding optical performance of the UIS2 Optical System.

That's why installing Olympus microscope components is, quite simply, the right choice for your equipment.

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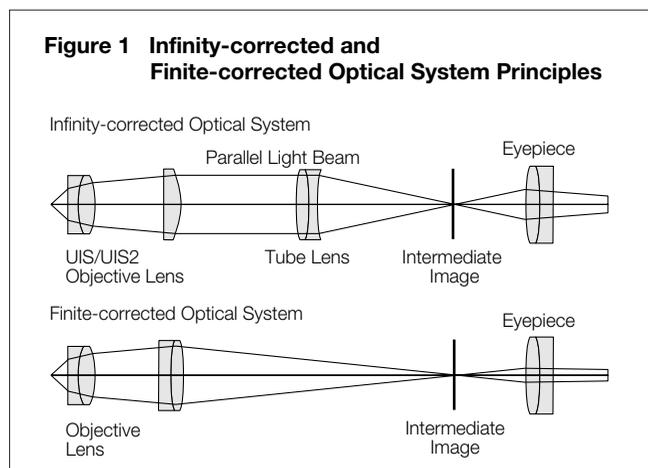
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UIS2:

The System That Maximizes the Advantage of Infinity-corrected Optics

What is Infinity-corrected Optics?

UIS2 optics is an infinity-corrected optical system — in other words, a system in which light passes from the specimen through the objective lens without forming an image along the way. Instead, it travels in the form of infinity parallel rays to the tube lens. The tube lens is where the intermediate image is formed, whereas in finite-corrected optics, this is done by the objective lens.



Advantages of Infinity-corrected Optics

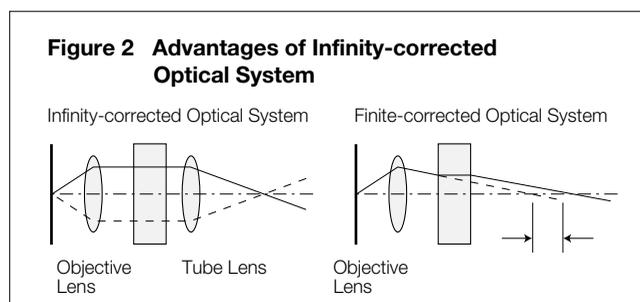
This system, known as "infinity-corrected optics", offers a number of advantages:

- There is no change in magnification even when the distance between the objective lens and tube lens is altered.
- With the total magnification remaining constant, there is no image aberration — even when prisms or sliders are interposed between the objective lens and the tube lens.

As thousands of users have found by experience, these advantages are crucial to composing the ideal microscope optical system. What's more, it is even possible to freely insert or remove intermediate attachments in the parallel rays of

light between the objective lens and tube lens, allowing the creation of user-specific or task-specific optical systems. To establish real flexibility with such a system, it is necessary to eliminate the occurrence of coma aberration.

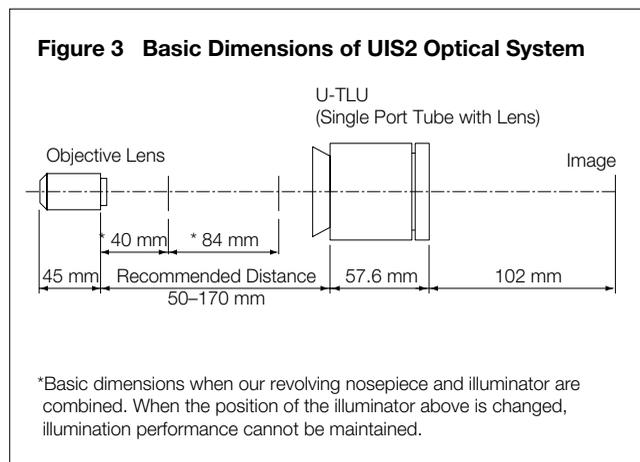
**In UIS2 objective lenses, the parfocal distance is designed at 45 mm and the focal length of the tube lens is 180 mm.*



Basic Dimensions of UIS2 Optical System

The UIS2 optical system optimally corrects aberration with a dedicated telan lens and an eyepiece so that the coma aberration and flatness are not degraded even when the telan lens exit pupil position is changed by changing the objective lens and telan distance. This makes it possible to use a distance of 50 mm to 170 mm from objective lens mounting position to the single port tube with lens.

**Coma aberration: refer to the optical terminology at the end of this document.*



**Basic dimensions when our revolving nosepiece and illuminator are combined. When the position of the illuminator above is changed, illumination performance cannot be maintained.*

Features of UIS2 Objective Lenses

UIS2 objective lenses ensure compatibility (screw diameter, optical performance) with the UIS optical system and have the following features compared to conventional objective lenses.

1. Wavefront Aberration Control

The Olympus UIS2 objective lenses set a new standard, with wavefront aberration control in addition to common performance standards of N.A. and W.D. Olympus challenges farther high order optics which has not been fulfilled by the conventional standards. We offer excellent performance objective lenses by minimizing the aberrations that lower resolution.

**Wave front aberration: refer to the optical terminology at the end of this document.*

2. Objective Lenses with Excellent Image Parcentricity

High power SemiApochromatic UIS2 objective lenses make the centration tolerance between objective lenses on the microscope nosepiece keep the image within the center of the field of view even with digital cameras. (50x or higher power in both MPLFLN and LMPLFLN series)

3. Improvement of Color Reproducibility

UIS2 objective lenses realize natural color reproduction without any chromatic shifts using stringently selected high transmittance glass and advanced coating technology that provides high transmittance which is flat over an ultra-wide band wavelength. In addition, since the total optical system, including the tube lens is designed to reproduce a natural color, clear images faithful to the specimen are obtained even with digital imaging.

4. Lightening

Weight has been reduced to approximately 2/3 that of conventional products by using an aluminum objective lens barrel cover. This has the effect of lightening the load on the devices at objective lens up/down, suppressing vibrations by lowering the inertial force at objective lens switching, etc. (MPLFLN series, LMPLFLN series)

5. Adoption of Eco-lens

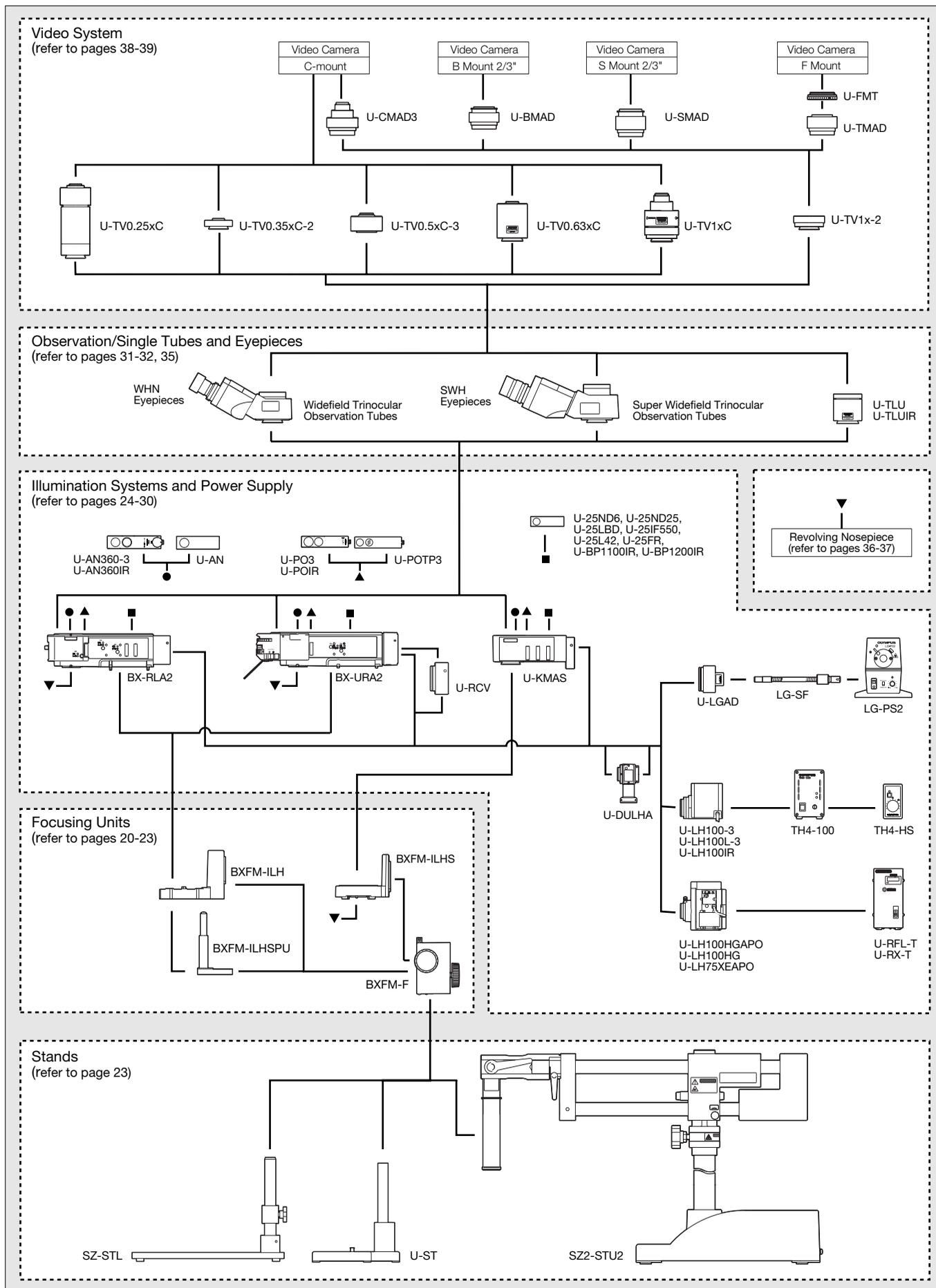
The glass materials of UIS2 objective lenses are all lead- and cadmium-free eco-glass.

Based on our conviction that the UIS2 system is the best way to maximize the advantages of infinity-corrected optical systems, we confidently recommend the UIS2-featured Olympus microscope units for all your high-precision needs in research, inspection and production equipment.

** Refer to the Olympus home page for detailed objective lenses specifications.*

System Diagram

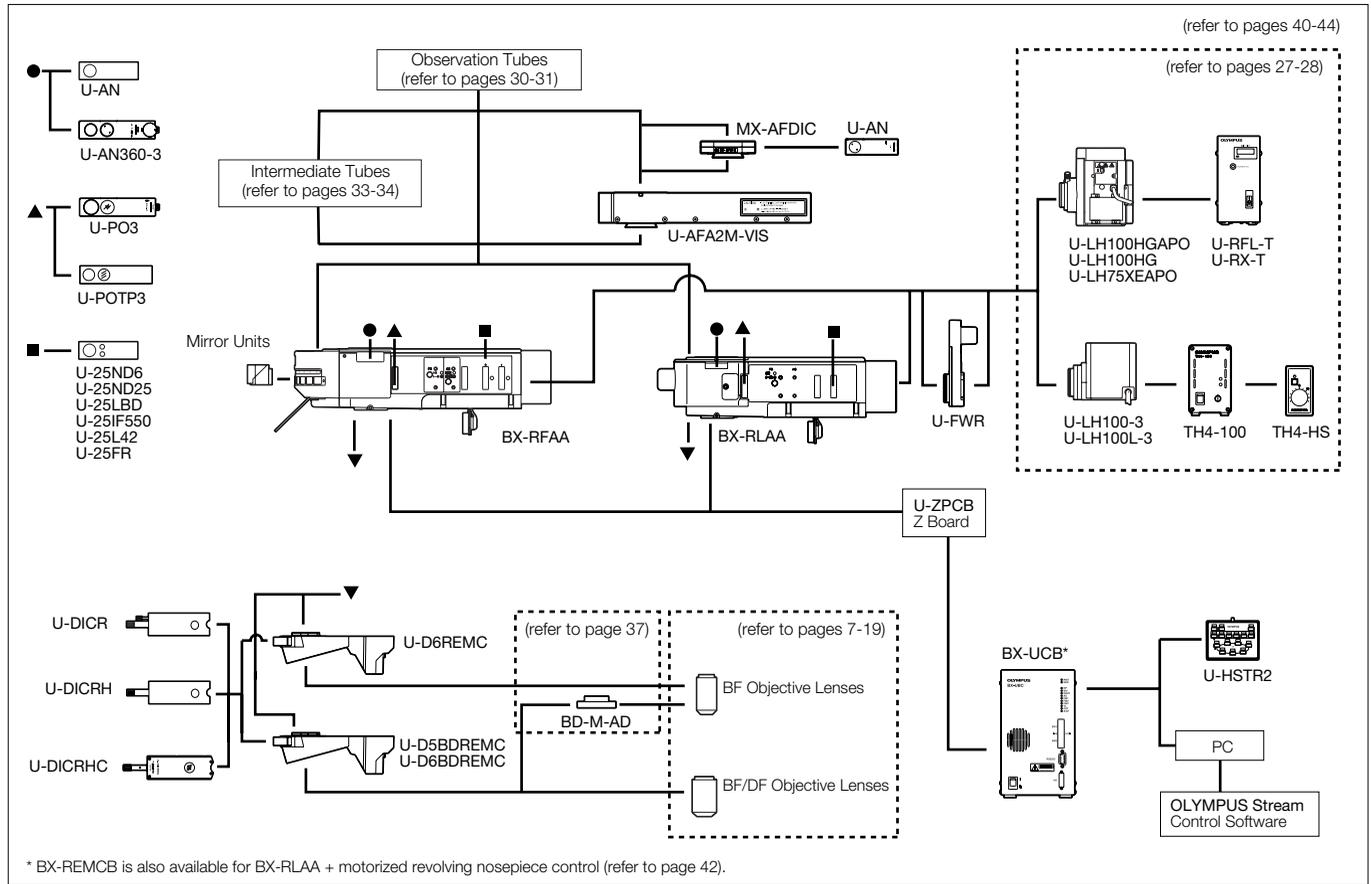
BXFM System Diagram



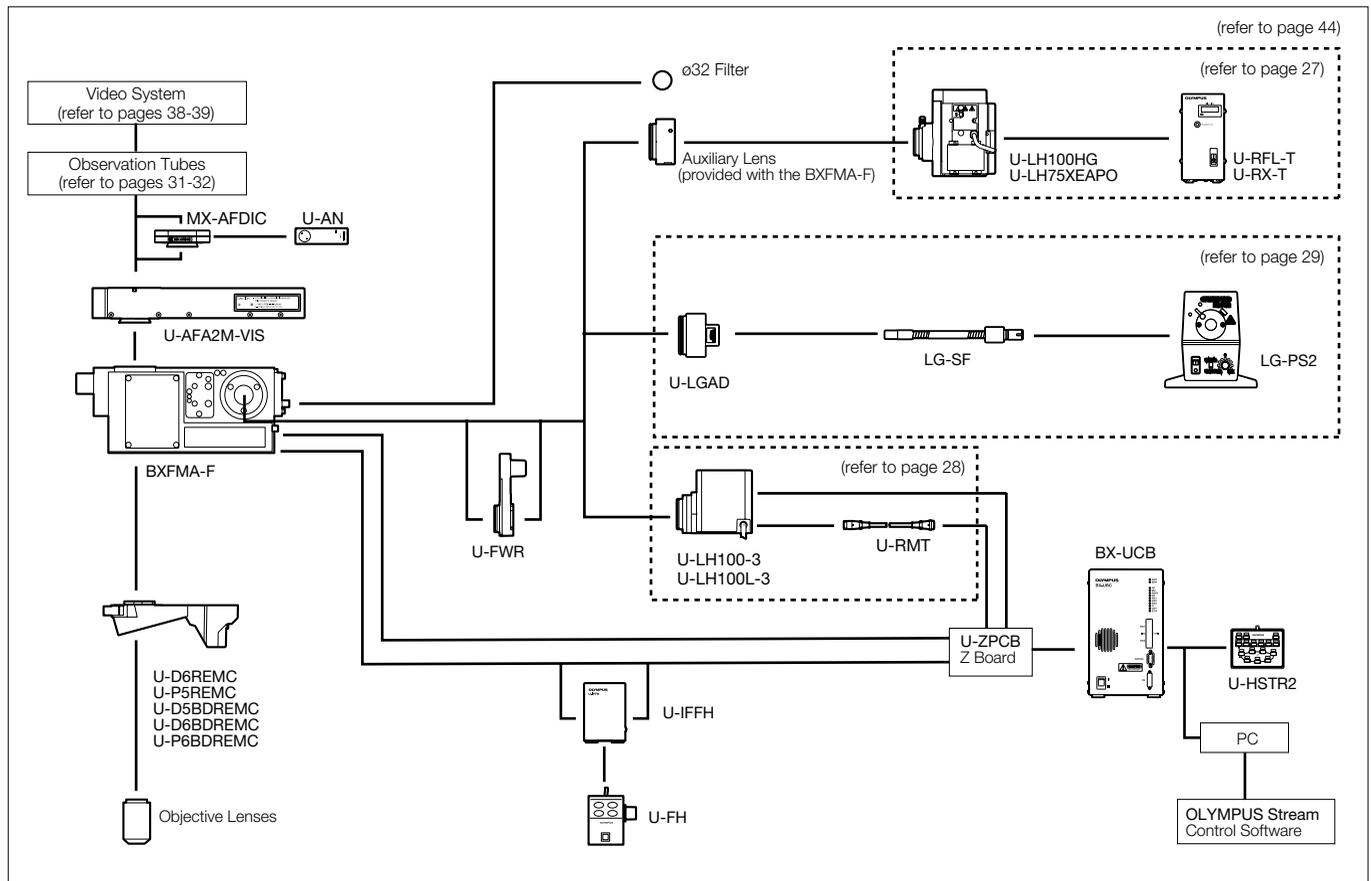
*Different types may be offered in each area.

System Diagram

Motorized Unit System Diagram

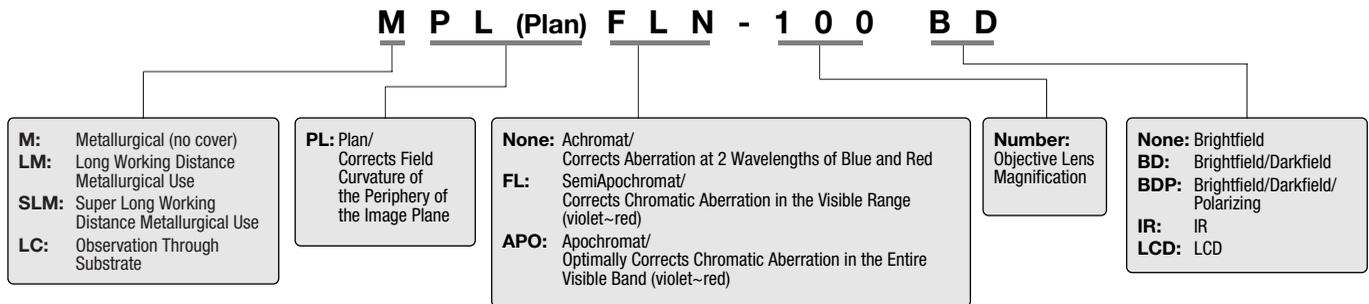


BXFM-A System Diagram

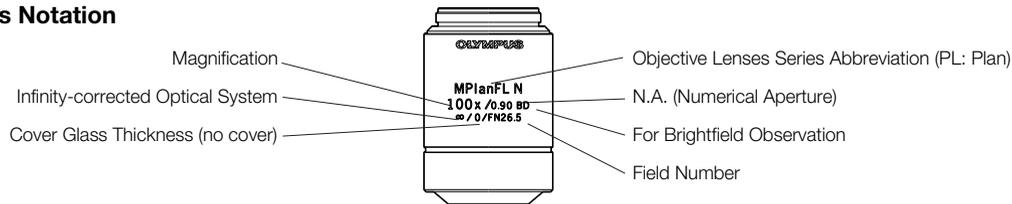


UIS2 Objective Lenses

■ Meaning of Abbreviations Shown on Objective Lens



■ Objective Lens Notation



■ Objective Lens Series List

Series	Magnification	BF	DF	DIC*	POL	FL	F.N. (Field Number)	Remarks
MPLAPON	50/100	○		○ U	○		26.5	
MPLAPON O	100	○					26.5	
MPLFLN	1.25/2.5	○					1.25x; 22 /2.5x; 26.5	Use together with polarizer and analyzer recommended.
	5/10/20/40*/50/100	○		○ U	○	○ ³	26.5	
LMPLFLN	5/10/20/50/100	○		○ L	○	○	26.5	
MPLN	5/10/20/50/100	○					22	
LCPLFLN-LCD	20/50/100	○		○ L			26.5	for LCD
SLMPLN	20/50/100	○					26.5	
LMPLN-IR	5/10	○					22	for near-IR observation
LCPLN-IR	20/50/100	○					22	for near-IR observation
MPLFLN-BD	5/10/20/50/100/150	○	○	○ U	○	○ ³	26.5	
MPLFLN-BDP	5/10/20/50/100	○	○	● U	●	○ ³	26.5	
LMPLFLN-BD	5/10/20/50/100	○	○	○ L	○	○	26.5	
MPLN-BD	5/10/20/50/100	○	○				22	

*1 DIC Prism U-DICR: UM/LM Position, U-DICRHC: LM Position Fixed, U-DICRH: UM Position Fixed. *2 40x: BF Only *3 5-20x: U Excitation Also Possible
○: Responds ●: Optimally Responds BF: Brightfield DF: Darkfield DIC: Differential Interference Contrast POL: Polarized light FL: Fluorescence

■ Features of Objective Lens Series

● MPLAPON Series: M Plan Apochromat — P 8

Plan Apochromat objective lenses that correct chromatic aberrations at optimal level among Olympus objective lenses. Olympus guarantees* optical performance (wavefront aberration) with a Strehl ratio** of 95% or better. They are also designed for use with Olympus' U-AFA2M active AF unit.

● MPLAPON 100x0: M Plan Apochromat — P 8

This is a Plan Apochromat objective lens of the oil-immersion type*** that features a numerical aperture of 1.4. It provides excellent chromatic aberration correction and a high resolving power.

● MPLFLN Series: M Plan SemiApochromat — P 9

Plan SemiApochromat objective lenses, giving high-level correction for chromatic aberration. The lineup consists of 8 objective lenses ranging from 1.25x to 100x, and secures a W.D. of 1 mm or longer (except 40x). Since the exit pupil position of the 5x-100x objective lenses is standardized, the position of the DIC prism does not have to be switched when changing the magnification (40x is not applicable to DIC observation). For ultra low magnifications (1.25x, 2.5x), use together with analyzer and polarizer of the reflected light illuminator.

● LMPLFLN Series: Long WD M Plan SemiApochromat — P 10

Long working distance Plan SemiApochromat objective lenses, giving high-level correction for chromatic aberration. Suitable with samples having a height difference and in preventing collision, as the working distance is long. Also, since the exit pupil position of the 5x-100x objective lenses is standardized, the position of the DIC prism does not have to be switched when changing the magnification.

● MPLN Series: M Plan Achromat — P 11

Plan Achromat objective lenses providing excellent image flatness up to F.N. 22.

● LCPLFLN-LCD Series: LCD Long WD M Plan SemiApochromat — P 12

Perfect objective lens series for observation of LCD panels and other samples through a glass substrate. Aberration correction matched to the glass thickness is accomplished using a correction collar.

● SLMPLN Series: Super Long WD M Plan Achromat — P 13

Plan Achromat objective lenses with high magnification and super long working distance. Three magnifications, 20x, 50x and 100x are available. For 5x or 10x objective lenses, select from the LMPLFLN Series.

● LMPLN-IR Series: IR Long WD M Plan Achromat — P 14

Objective lens series exclusive for the near-infrared microscopy largely of the internal structure in silicon wafers.

● LCPLN-IR Series: IR Long WD M Plan Achromat — P 15

Exclusive for the near-infrared microscopy largely of the internal structure in silicon wafers, LCPLN-IR series has correction collar for aberration dependent on thickness of silicon or glass substrate.

● MPLFLN-BD Series: M Plan SemiApochromat BD — P 16

Plan SemiApochromat objective lenses, giving high-level correction for chromatic aberration. The series secures a W.D. of 1 mm or longer. Since the exit pupil position of the 5x-150x objective lenses is standardized, the position of the DIC prism does not have to be switched when changing the magnification.

● MPLFLN-BDP Series: M Plan SemiApochromat BDP — P 17

Plan SemiApochromat objective lenses, giving high-level correction for chromatic aberration. The series secures a W.D. of 1 mm or longer. Since the exit pupil position of the 5x-100x objective lenses is standardized, the position of the DIC prism does not have to be switched when changing the magnification. The BDP series optimizing brightfield/darkfield and polarized light characteristics is perfect for Nomarski DIC and polarized light observations.

● LMPLFLN-BD Series: Long WD M Plan SemiApochromat BD — P 18

Long working distance Plan SemiApochromat objective lenses, giving high-level correction for chromatic aberration. Suitable with samples having a height difference and in preventing collision, as the working distance is long. Also, since the exit pupil position of the 5x-100x objective lenses is standardized, the position of the DIC prism does not have to be switched when changing the magnification.

● MPLN-BD Series: M Plan Achromat BD — P 19

Plan Achromat objective lenses providing excellent image flatness up to F.N. 22.

* Definition of guaranteed values: Measurements assessed with Olympus' Interferometer for Transmitted Wavefront Measurement under specified conditions (measurement: temp. 23°C±1°C; assessment: measurement within the 97% range of the pupil dia.).

** Strehl ratio: Indicates in percent (%) the ratio of the proportion of light that an actual optical system can concentrate with respect to the proportion of light concentrated in the image plane (central intensity) by an ideal, aberration-free optical system, with the latter serving as 100%. A higher percentage indicates a higher quality optical system.

*** Specified oil: IMMOIL-F30CC

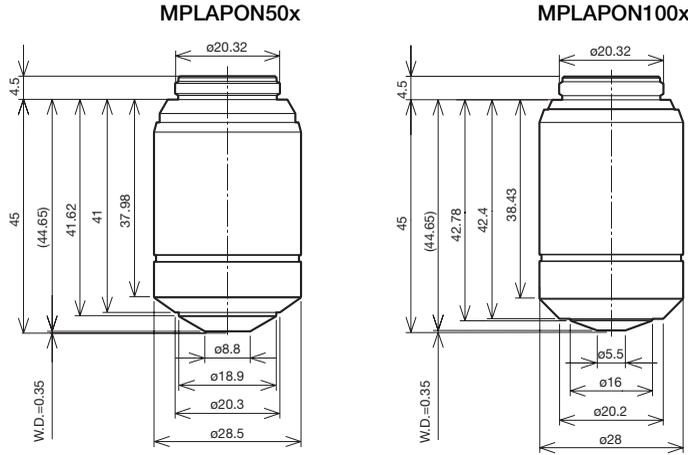
M Plan Apochromat

MPLAPON Series



Plan Apochromat objective lenses that correct chromatic aberrations at optimal level among Olympus objective lenses.

Olympus guarantees* optical performance (wavefront aberration) with a Strehl ratio** of 95% or better. They are also designed for use with Olympus' U-AFA2M active AF unit.



* Definition of guaranteed values: Measurements assessed with Olympus' Interferometer for Transmitted Wavefront Measurement under specified conditions (measurement: temp. 23°C±1°C; assessment: measurement within the 97% range of the pupil dia.).

** Strehl ratio: Indicates in percent (%) the ratio of the proportion of light that an actual optical system can concentrate with respect to the proportion of light concentrated in the image plane (central intensity) by an ideal, aberration-free optical system, with the latter serving as 100%. A higher percentage indicates a higher quality optical system.

Unit: mm

UIS2 Objective Lenses					Widefield Eyepiece WHN10x Field Number 22			Super Widefield Eyepiece SWH10x Field Number 26.5		
Objective Lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)
MPLAPON 50x	0.95	0.35	3.6	139	500	0.44	1.0	500	0.53	1.0
MPLAPON 100x	0.95	0.35	1.8	125	1000	0.22	0.67	1000	0.27	0.7

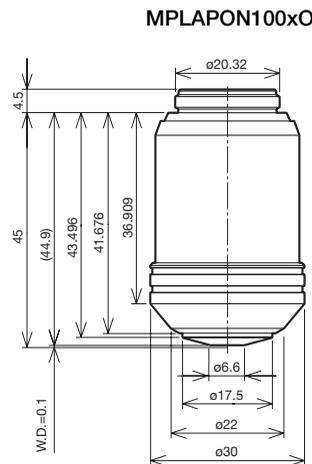
Screw: W20.32x0.706 (0.8"x1/36")

M Plan Apochromat

MPLAPON 100xO



This is a Plan Apochromat objective lens of the oil-immersion type*** that features a numerical aperture of 1.4. It provides excellent chromatic aberration correction and a high resolving power.



*** Specified Oil: IMMOIL-F30CC

Unit: mm

UIS2 Objective Lenses					Widefield Eyepiece WHN10x Field Number 22			Super Widefield Eyepiece SWH10x Field Number 26.5		
Objective Lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)
MPLAPON 100xO	1.4	0.1	1.8	158	1000	0.22	0.59	1000	0.27	0.59

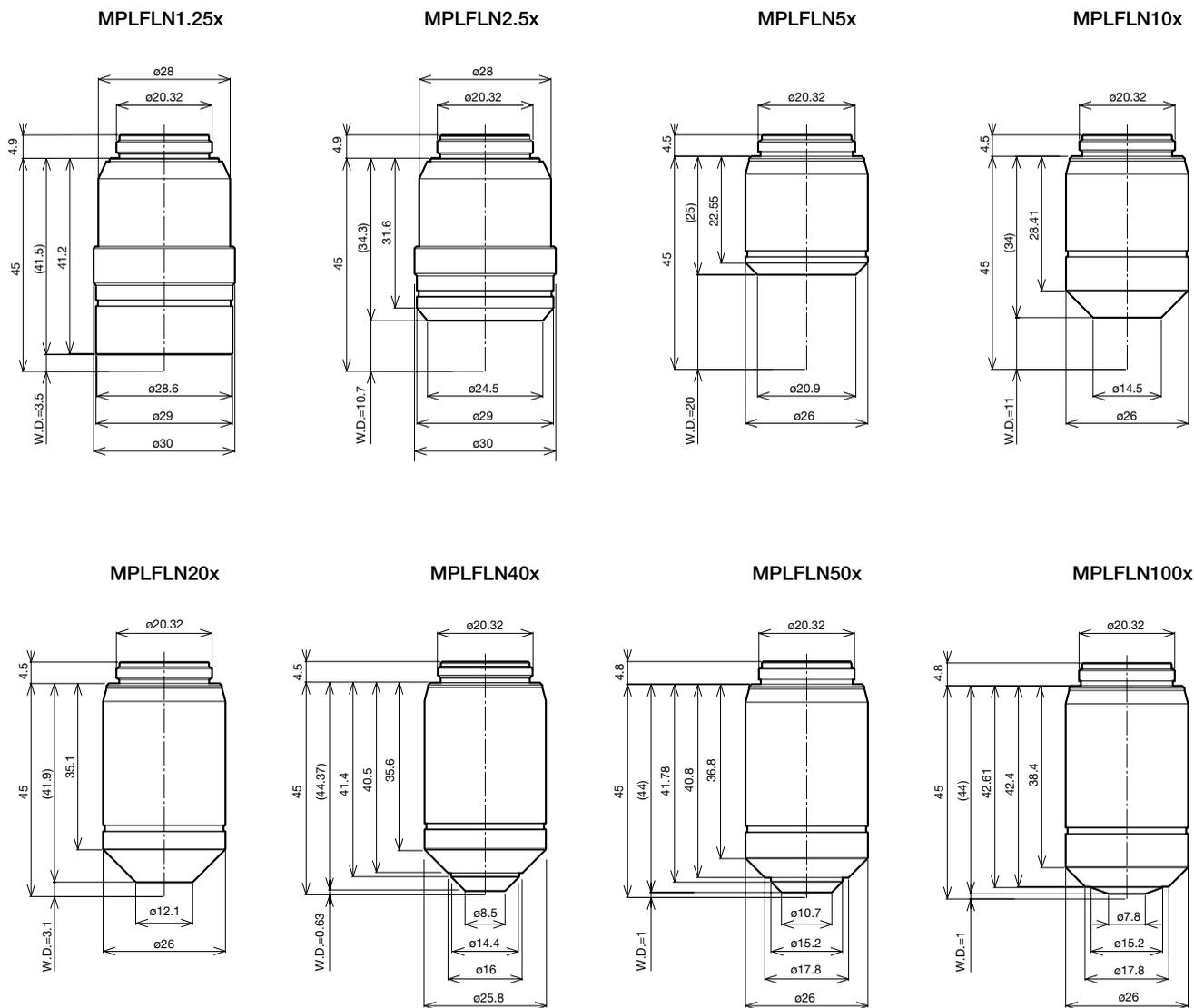
Screw: W20.32x0.706 (0.8"x1/36")

UIS2 Objective Lenses

M Plan SemiApochromat MPLFLN Series



Plan SemiApochromat objective lenses, giving high-level correction for chromatic aberration. The lineup consists of 8 objective lenses ranging from 1.25x to 100x, and secures a W.D. of 1 mm or longer (except 40x). Since the exit pupil position of the 5x–100x objective lenses is standardized, the position of the DIC prism does not have to be switched when changing the magnification (40x is not applicable to DIC observation). For ultra low magnifications (1.25x, 2.5x), use together with analyzer and polarizer of the reflected light illuminator.



Unit: mm

UIS2 Objective Lenses					Widefield Eyepiece WHN10x Field Number 22			Super widefield Eyepiece SWH10x Field Number 26.5		
Objective Lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (μm)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (μm)
MPLFLN 1.25x	0.04	3.5	145	122	12.5	17.6	870	—	—	—
MPLFLN 2.5x	0.08	10.7	72	106	25	8.8	220	25	10.6	220
MPLFLN 5x	0.15	20.0	36	51.5	50	4.4	59	50	5.3	59
MPLFLN 10x	0.30	11.0	18	68.1	100	2.2	15	100	2.7	15
MPLFLN 20x	0.45	3.1	9	70.4	200	1.1	5.2	200	1.3	5.1
MPLFLN 40x	0.75	0.63	4.5	120	400	0.55	1.66	400	0.66	1.66
MPLFLN 50x	0.80	1.0	3.6	89.9	500	0.44	1.3	500	0.53	1.3
MPLFLN 100x	0.90	1.0	1.8	90.9	1000	0.22	0.73	1000	0.27	0.73

Screw: W20.32x0.706 (0.8"x1/36")

UIS2 Objective Lenses

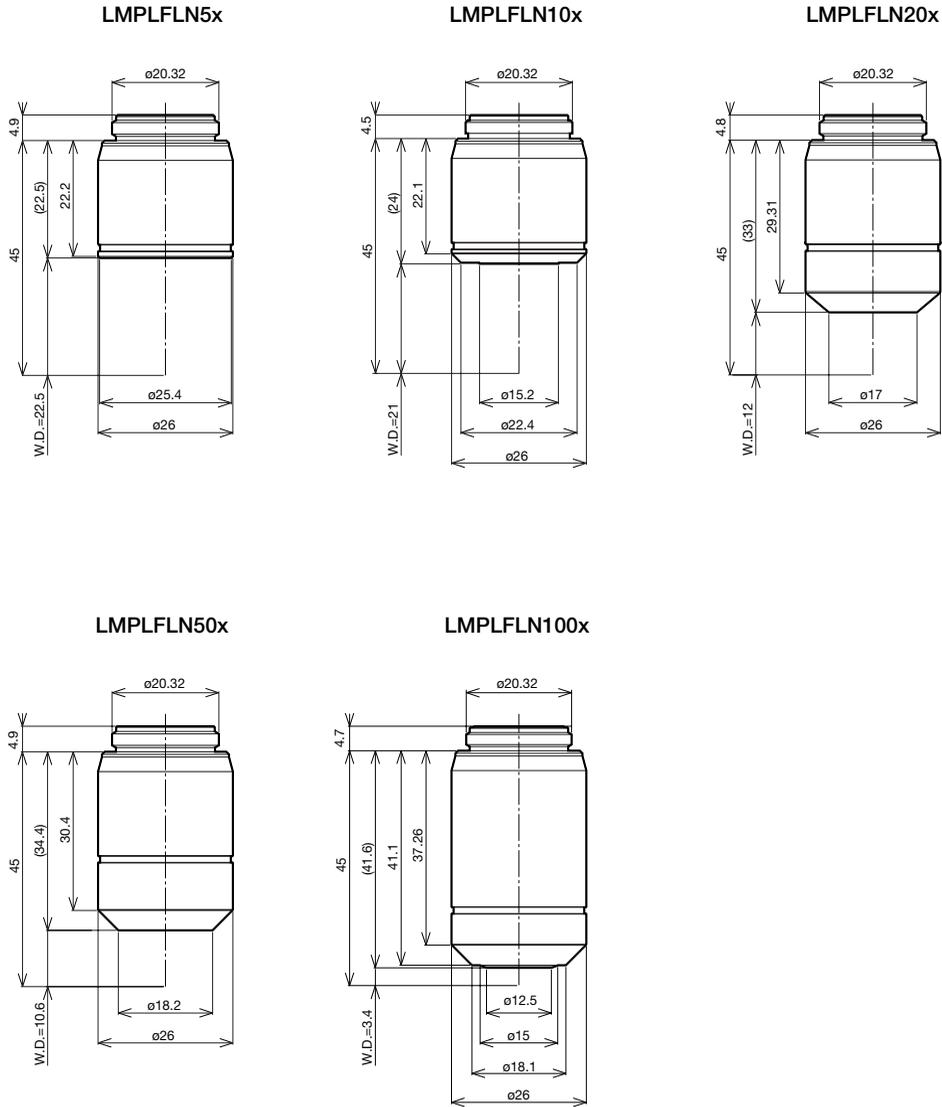
Long WD M Plan SemiAchromat

(W.D.: Working Distance)

LMPLFLN Series



Long working distance Plan SemiAchromat objective lenses, giving high-level correction for chromatic aberration. Suitable with samples having a height difference and in preventing collision, as the working distance is long. Also, since the exit pupil position of the 5x–100x objective lenses is standardized, the position of the DIC prism does not have to be switched when changing the magnification.



Unit: mm

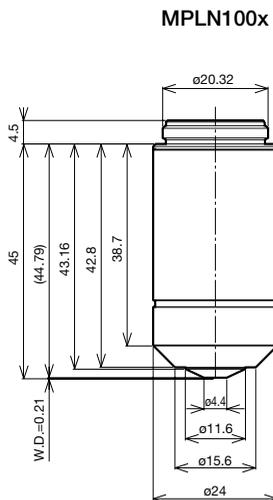
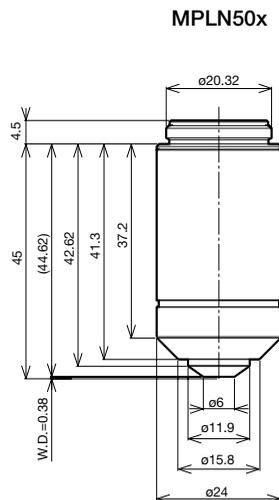
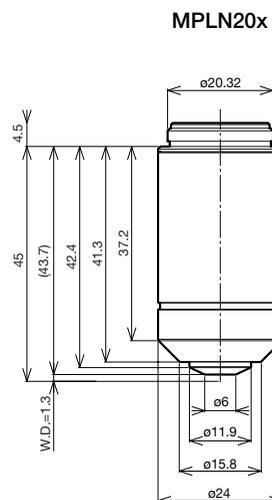
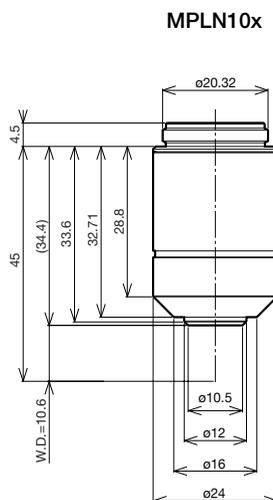
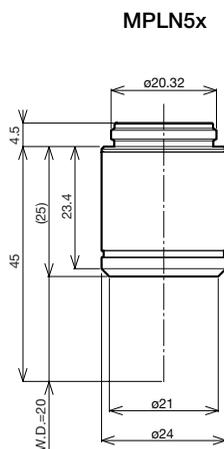
UIS2 Objective Lenses					Widefield Eyepiece WHN10x Field Number 22			Super Widefield Eyepiece SWH10x Field Number 26.5		
Objective lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (μm)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (μm)
LMPLFLN 5x	0.13	22.5	36	50	50	4.4	70	50	5.3	70
LMPLFLN 10x	0.25	21.0	18	54	100	2.2	18	100	2.7	18
LMPLFLN 20x	0.40	12.0	9	73	200	1.1	6.1	200	1.3	6.1
LMPLFLN 50x	0.50	10.6	3.6	77	500	0.44	2.5	500	0.53	2.5
LMPLFLN 100x	0.80	3.4	1.8	94	1000	0.22	0.87	1000	0.27	0.87

Screw: W20.32x0.706 (0.8"x1/36")

M Plan Achromat

MPLN Series

Plan Achromat objective lenses providing excellent image flatness up to F.N. 22.



Unit: mm

UIS2 Objective Lenses					Widefield Eyepiece WHN10x Field Number 22		
Objective Lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (μ m)
MPLN 5x	0.10	20.0	36	64	50	4.4	98
MPLN 10x	0.25	10.6	18	80	100	2.2	18
MPLN 20x	0.40	1.3	9	111	200	1.1	6.1
MPLN 50x	0.75	0.38	3.6	113	500	0.44	1.4
MPLN 100x	0.90	0.21	1.8	116	1000	0.22	0.73

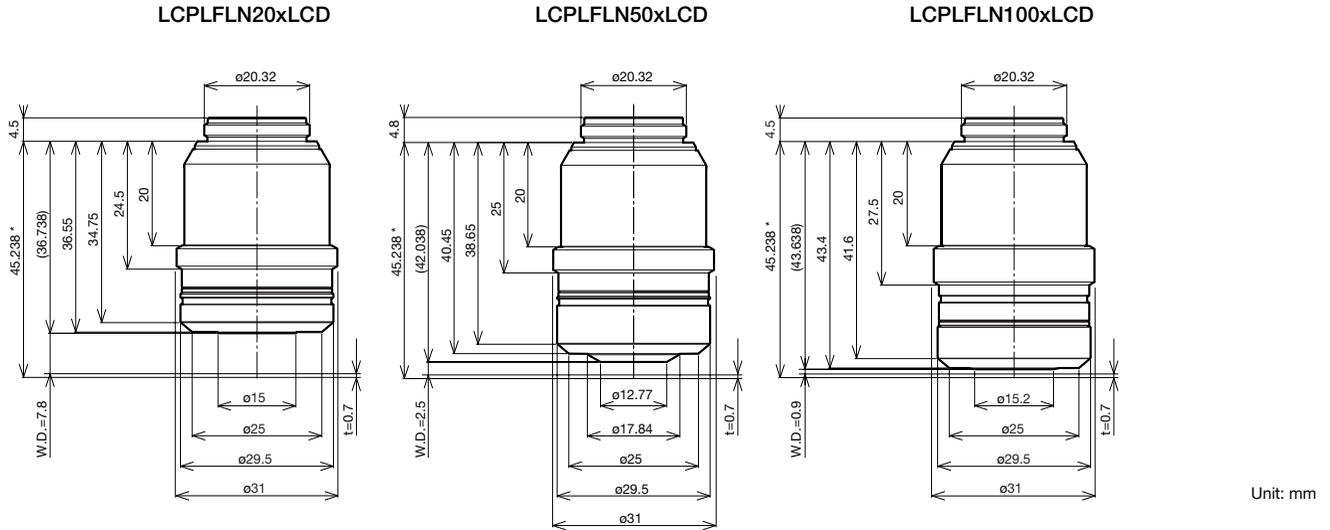
Screw: W20.32x0.706 (0.8"x1/36")

LCD Long WD M Plan SemiApochromat

LCPLFLN-LCD Series



Perfect objective lens series for observation of LCD panels and other samples through a glass substrate. Aberration correction matched to the glass thickness is accomplished using a correction collar.



* Value at glass thickness 0.7 mm observation.

Objective Lens	LCPLFLN20xLCD			LCPLFLN50xLCD			LCPLFLN100xLCD		
Corresponding Glass Thickness (mm)	0-1.2			0-1.2			0-0.7		
Correction Collar Indication	0	0.7	1.2	0	0.7	1.2	0	0.5	0.7
Working Distance (mm)	8.3	7.8	7.4	3.0	2.5	2.2	1.2	0.98	0.9
Correction System	Correction Collar			Correction Collar			Correction Collar		

UIS2 Objective Lenses					Widfield Eyepiece WHN10x Field Number 22			Super widefield Eyepiece SWH10x Field Number 26.5		
Objective Lens (magnification)	Numerical Aperture	Working Distance** (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)
LCPLFLN 20xLCD	0.45	7.8	9	146	200	1.1	5.2	200	1.3	5.2
LCPLFLN 50xLCD	0.70	2.5	3.6	170	500	0.44	1.6	500	0.53	1.6
LCPLFLN 100xLCD	0.85	0.9	1.8	185	1000	0.22	0.79	1000	0.27	0.79

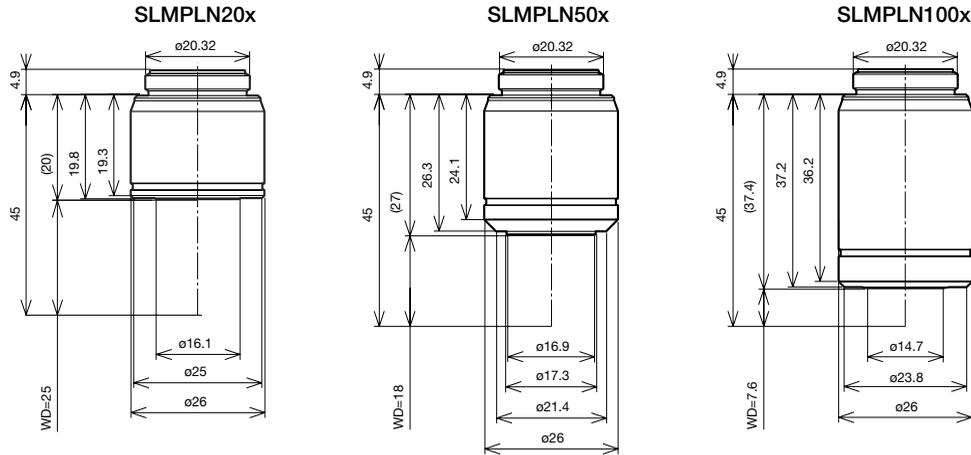
Screw: W20.32x0.706 (0.8"x1/36") **The figure shown here is the value when the correction collar indication is 0.7.

Super Long WD M Plan Achromat

SLMPLN Series



Plan Achromat objective lenses with high magnification and super long working distance. Three magnifications, 20x, 50x and 100x are available. For 5x or 10x objective lenses, select from the LMPLFLN series.



Unit: mm

UIS2 Objective Lenses					Widefield Eyepiece WHN10x Field Number 22			Super Widefield Eyepiece SWH10x Field Number 26.5		
Objective Lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (μm)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (μm)
SLMPLN 20x	0.25	25	9	56	200	1.1	11.4	200	1.3	11.4
SLMPLN 50x	0.35	18	3.6	74	500	0.44	4.2	500	0.53	4.2
SLMPLN 100x	0.6	7.6	1.8	100	1000	0.22	1.3	1000	0.27	1.3

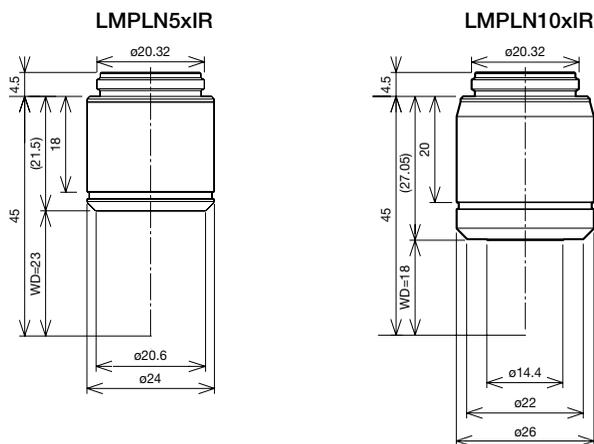
Screw: W20.32x0.706 (0.8"x1/36")

IR Long WD M Plan Achromat

LMPLN-IR Series



Objective lens series exclusive for the near-infrared microscopy largely of the internal structure in silicon wafers.



Unit: mm

UIS Objective Lenses				
Objective Lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)
LMPLN 5xIR	0.1	23	36	55
LMPLN 10xIR	0.3	18	18	78

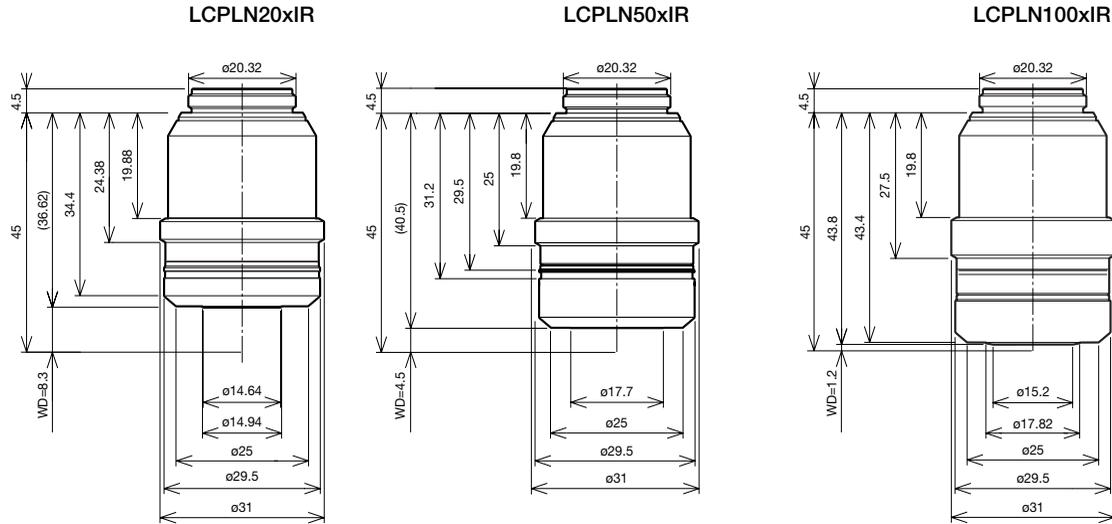
Screw: W20.32x0.706 (0.8"x1/36")

IR M Plan Achromat

LCPLN-IR Series



Exclusive for the near-infrared microscopy largely of the internal structure in silicon wafers, LCPLN-IR series has correction collar for aberration dependent on thickness of silicon or glass substrate.



Unit: mm

Silicon thickness correction

Objective Lens	LCPLN20xIR			LCPLN50xIR			LCPLN100xIR		
Corresponding Silicon Thickness (mm)	0-1.2			0-1.2			0-1.0		
Correction Collar Indication	0	0.7	1.2	0	0.6	1.2	0	0.5	1
Working Distance* (mm)	8.3	8.2	8.0	4.5	4.3	4.1	1.2	1.1	1.0
Correction System	Correction Collar			Correction Collar			Correction Collar		

*With the use of 1100 nm laser.

Silicon thickness correction

Objective Lens	LCPLN20xLCD			LCPLN50xLCD			LCPLN100xLCD		
Corresponding Glass Thickness (mm)	0-1.2			0-1.2			0-0.7		
Correction Collar Indication	0	0.7	1.2	0	0.6	1.2	0	0.5	0.7
Working Distance* (mm)	8.3	7.9	7.6	4.5	3.7		1.2		0.9
Correction System	Correction Collar			Correction Collar			Correction Collar		

*With the use of 1064 nm laser.

UIS Objective Lenses				
Objective Lens (magnification)	Numerical Aperture*	Working Distance* (mm)	Focal Distance f (mm)	Weight (g)
LCPLN 20xIR	0.45	8.3	9	149
LCPLN 50xIR	0.65	4.5	3.6	169
LCPLN 100xIR	0.85	1.2	1.8	184

Screw: W20.32x0.706 (0.8"x1/36")

* The figure shown here is the value when the correction collar indication is 0.

UIS2 Objective Lenses

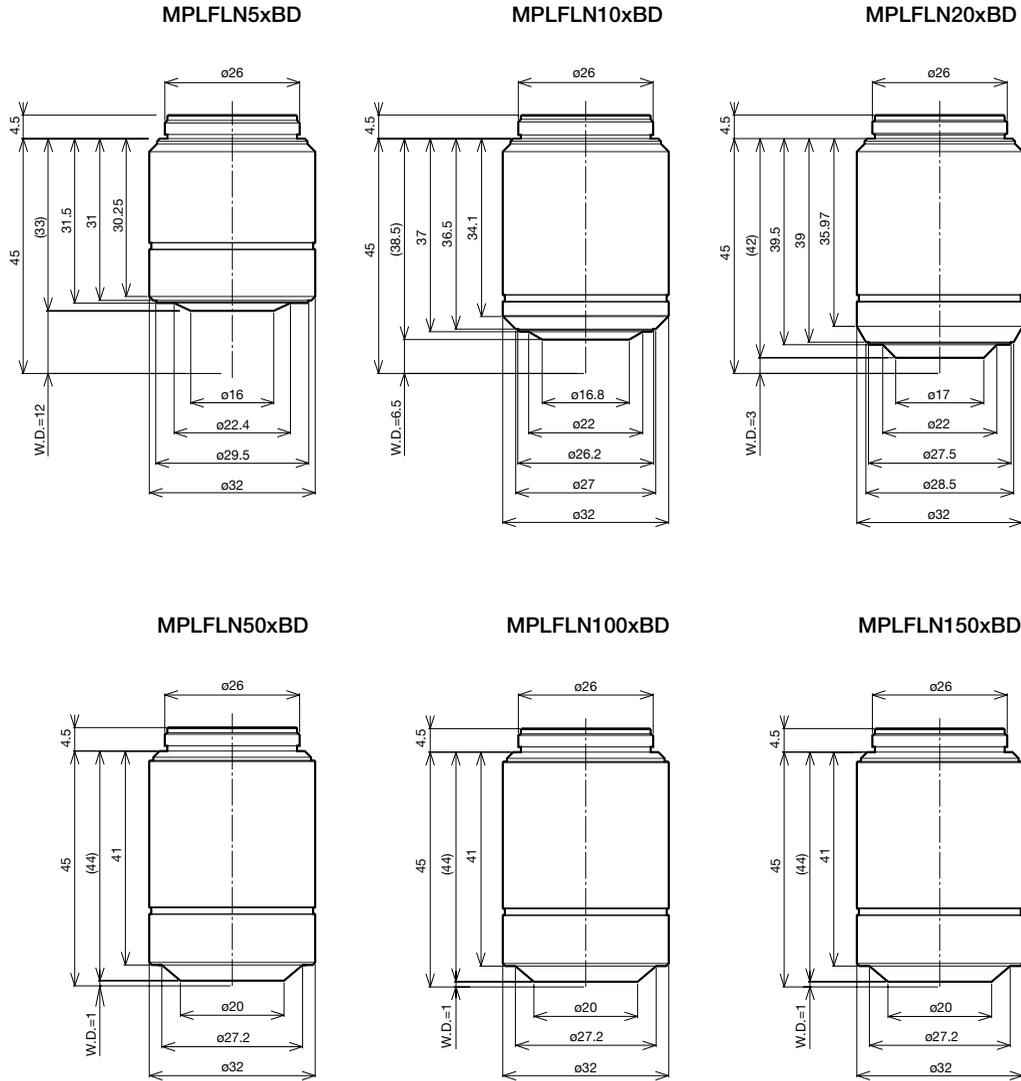
M Plan SemiApochromat BD

(BD: Brightfield/Darkfield)

MPLFLN-BD Series



Plan SemiApochromat objective lenses, giving high-level correction for chromatic aberration. The series secures a W.D. of 1 mm or longer. Since the exit pupil position of the 5x-150x objective lenses is standardized, the position of the DIC prism does not have to be switched when changing the magnification.



Unit: mm

UIS2 Objective Lenses					Widefield Eyepiece WHN10x Field Number 22			Super Widefield Eyepiece SWH10x Field Number 26.5		
Objective Lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)
MPLFLN 5xBD	0.15	12.0	36	95.5	50	4.4	59	50	5.3	59
MPLFLN 10xBD	0.30	6.5	18	82.8	100	2.2	15	100	2.7	15
MPLFLN 20xBD	0.45	3.0	9	87.7	200	1.1	5.2	200	1.3	5.2
MPLFLN 50xBD	0.80	1.0	3.6	99.8	500	0.44	1.3	500	0.53	1.3
MPLFLN 100xBD	0.90	1.0	1.8	98.9	1000	0.22	0.73	1000	0.27	0.73
MPLFLN 150xBD	0.90	1.0	1.2	104.8	1500	0.15	0.6	1500	0.18	0.6

Screw: W26x0.706

UIS2 Objective Lenses

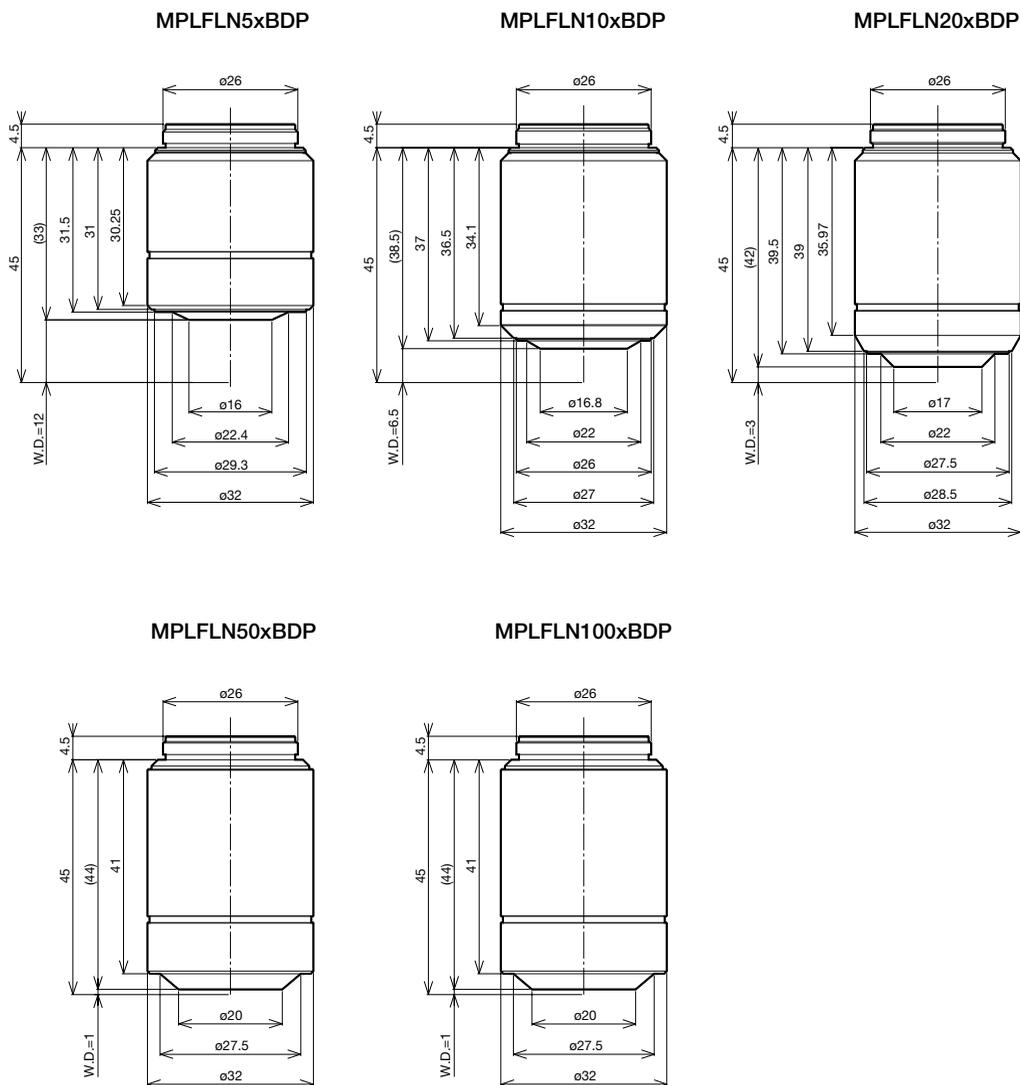
M Plan SemiApochromat BDP

(BDP: Brightfield/Darkfield/Polarizing)

MPLFLN-BDP Series



Plan SemiApochromat objective lenses, giving high-level correction for chromatic aberration. The series secures a W.D. of 1 mm or longer. Since the exit pupil position of the 5x-100x objective lenses is standardized, the position of the DIC prism does not have to be switched when changing the magnification. The BDP series optimizing brightfield/darkfield and polarized light characteristics is perfect for Nomarski DIC and polarized light observations.



Unit: mm

UIS2 Objective Lenses					Widefield Eyepiece WHN10x Field Number 22			Super Widefield Eyepiece SWH10x Field Number 26.5		
Objective Lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)
MPLFLN 5xBDP	0.15	12.0	36	95.5	50	4.4	59	50	5.3	59
MPLFLN 10xBDP	0.25	6.5	18	83.3	100	2.2	18	100	2.7	18
MPLFLN 20xBDP	0.40	3.0	9	88.5	200	1.1	6.1	200	1.3	6.1
MPLFLN 50xBDP	0.75	1.0	3.6	100.5	500	0.44	1.4	500	0.53	1.4
MPLFLN 100xBDP	0.90	1.0	1.8	101.5	1000	0.22	0.73	1000	0.27	0.73

Screw: W26x0.706

UIS2 Objective Lenses

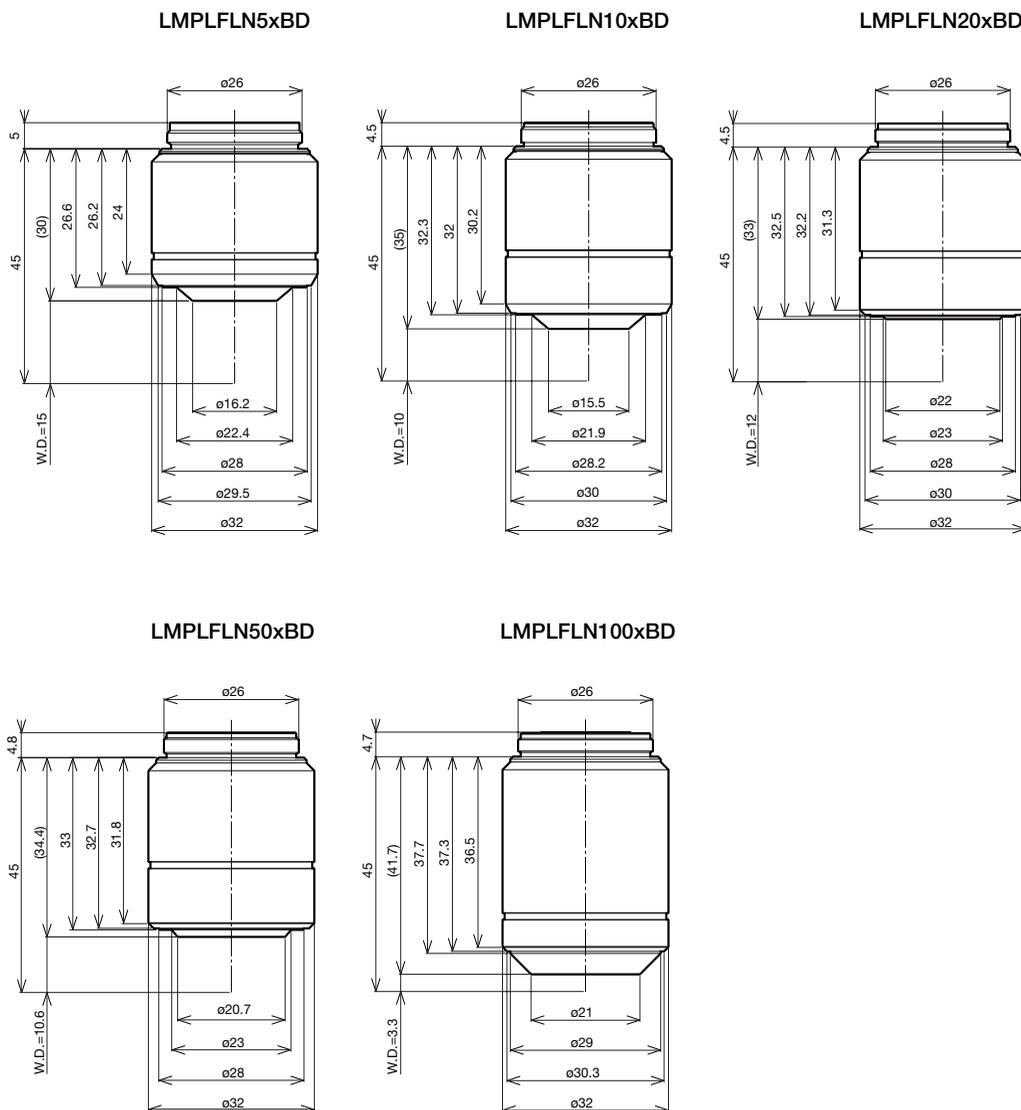
Long WD M Plan SemiApochromat BD

(BD: Brightfield/Darkfield)

LMPLFLN-BD Series



Long working distance Plan SemiApochromat objective lenses, giving high-level correction for chromatic aberration. Suitable with samples having a height difference and in preventing collision, as the working distance is long. Also, since the exit pupil position of the 5x-100x objective lenses is standardized, the position of the DIC prism does not have to be switched when changing the magnification.



Unit: mm

UIS2 Objective Lenses					Widefield Eyepiece WHN10x Field Number 22			Super Widefield Eyepiece SWH10x Field Number 26.5		
Objective Lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (µm)
LMPLFLN 5xBD	0.13	15.0	36	81	50	4.4	70	50	5.3	70
LMPLFLN 10xBD	0.25	10.0	18	84	100	2.2	18	100	2.7	18
LMPLFLN 20xBD	0.40	12.0	9	86	200	1.1	6.1	200	1.3	6.1
LMPLFLN 50xBD	0.50	10.6	3.6	85	500	0.44	2.5	500	0.53	2.5
LMPLFLN 100xBD	0.80	3.3	1.8	102	1000	0.22	0.87	1000	0.27	0.87

Screw: W26x0.706

UIS2 Objective Lenses

M Plan Achromat BD

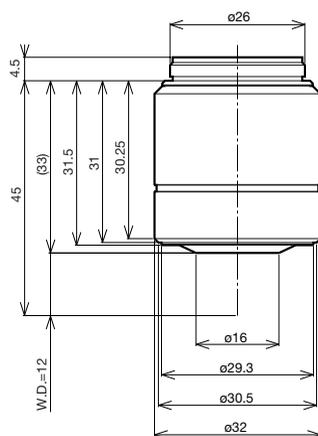
(BD: Brightfield/Darkfield)

MPLN-BD Series

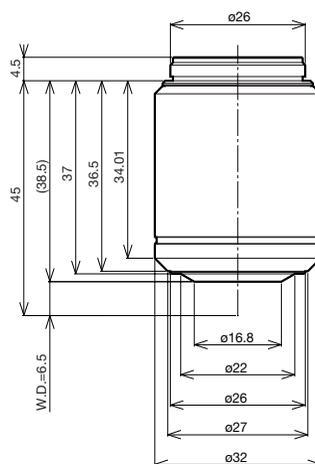
Plan Achromat objective lenses providing excellent image flatness up to F.N. 22.



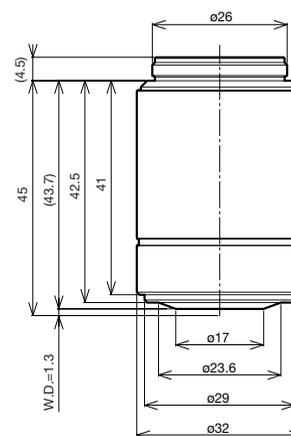
MPLN5xBD



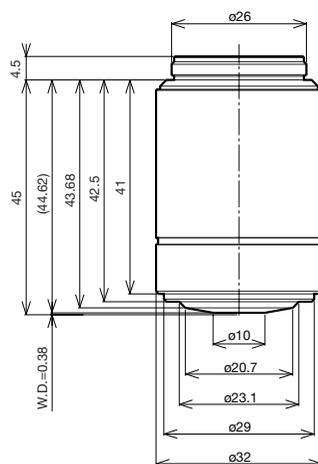
MPLN10xBD



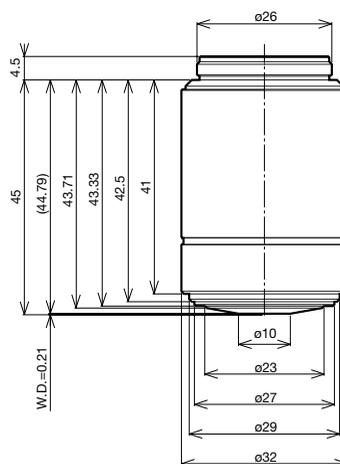
MPLN20xBD



MPLN50xBD



MPLN100xBD



Unit: mm

UIS2 Objective Lenses					Widefield Eyepiece WHN10x Field Number 22		
Objective Lens (magnification)	Numerical Aperture	Working Distance (mm)	Focal Distance f (mm)	Weight (g)	Total Magnifications	Practical Field of View (mm)	Depth of Focus (μm)
MPLN 5xBD	0.10	12.0	36	137	50	4.4	98
MPLN 10xBD	0.25	6.5	18	155	100	2.2	18
MPLN 20xBD	0.40	1.3	9	162	200	1.1	6.1
MPLN 50xBD	0.75	0.38	3.6	157	500	0.44	1.4
MPLN 100xBD	0.90	0.21	1.8	160	1000	0.22	0.73

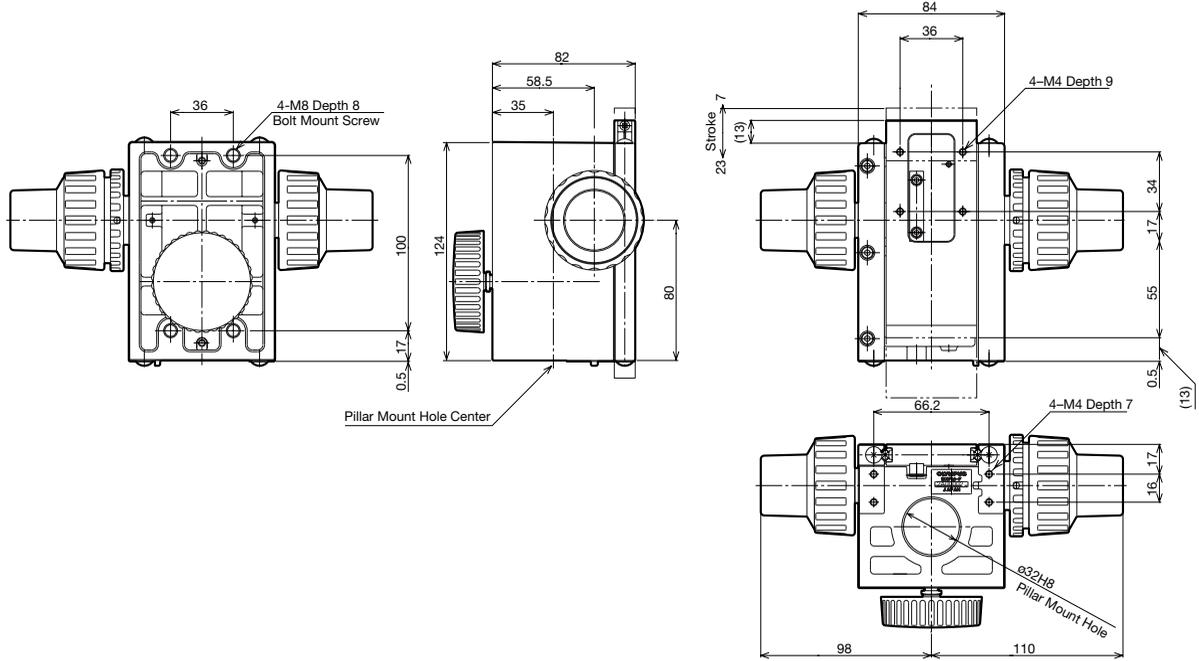
Screw: W26x0.706

Microscope System BXFM

BXFM Frame

BXFM-F

Widely used system that allows use in combination with fiber illumination, motorized revolving nosepiece and telan lens unit. Can easily be integrated into other equipment. Attach to the equipment by rear bolt mounting screw or pillar mounting hole.



Weight: 1.9kg

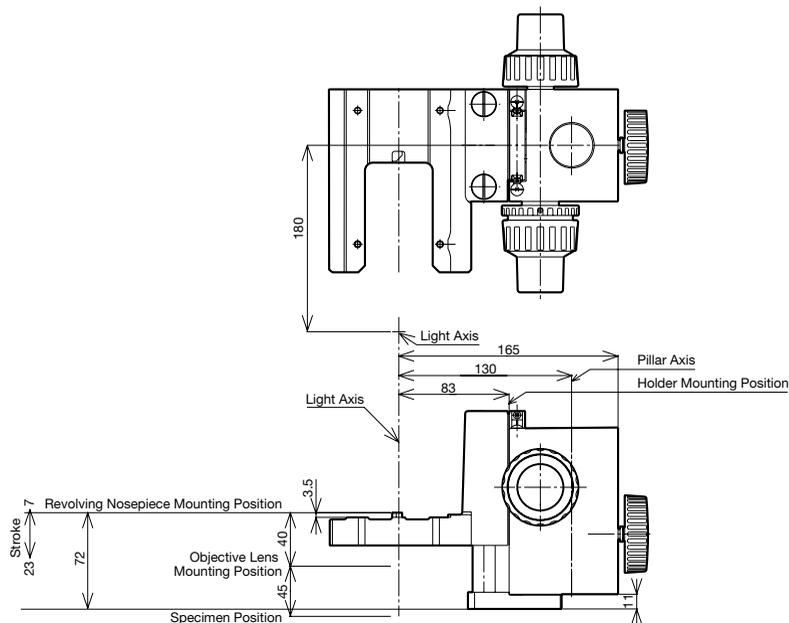
Unit: mm

Microscope System BXFM

BXFM

BXFM-F + BXFM-ILH + BXFM-ILHSPU

Accommodates the reflected light brightfield/darkfield and fluorescence illuminators.

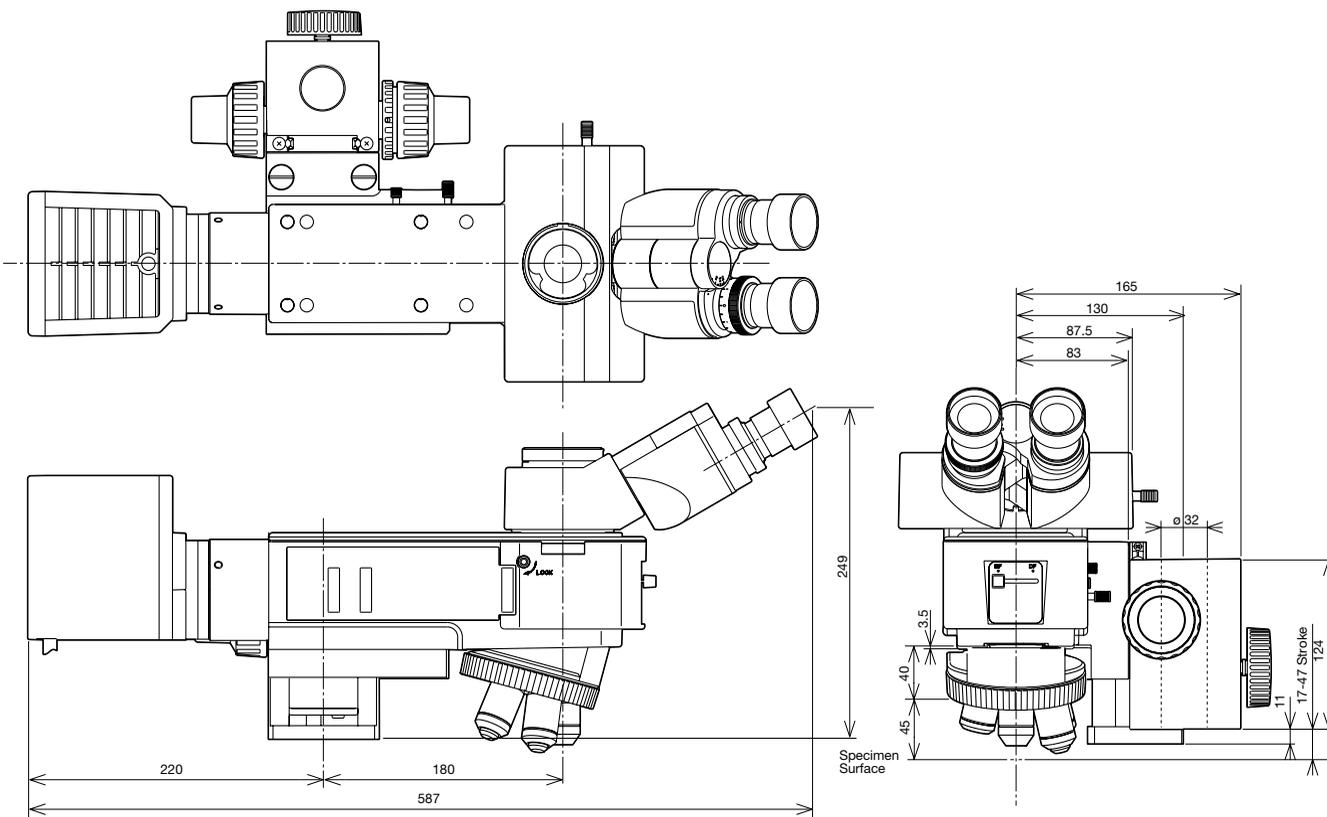


Weight: 3.2kg

Unit: mm

BXFM Combination Sample

BXFM-F + BXFM-ILH + BXFM-ILHSPU + TR30-2 + BX-RLA2 + U-LH100L-3



Weight: 8.2kg (exclude objective lens)

Unit: mm

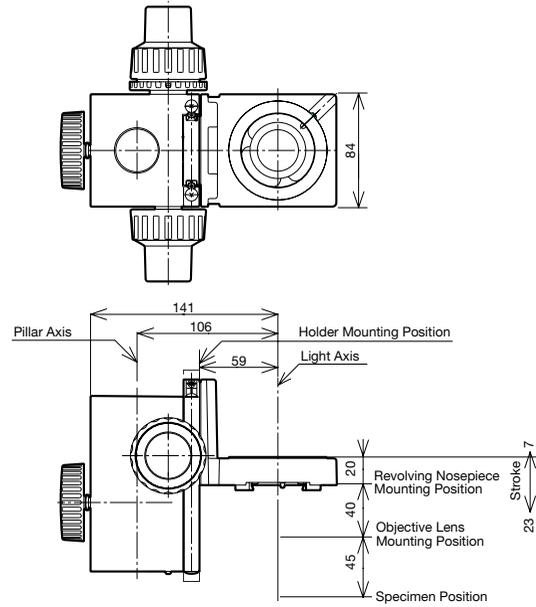
* For installation dimensions, refer to those for the BXFM-F.

Microscope System BXFM

BXFM-S

BXFM-F + BXFM-ILHS

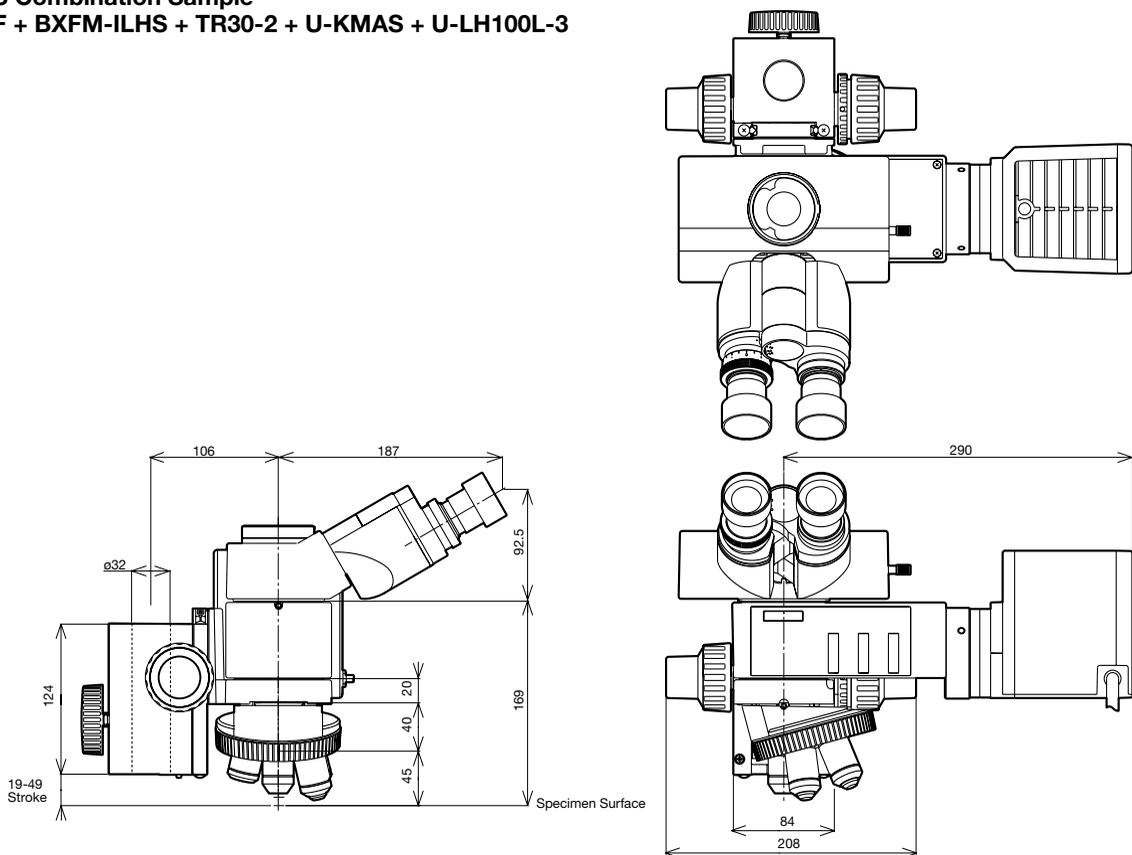
Compact focusing unit suitable for building into existing equipment.



Weight: 2.4kg

Unit: mm

BXFM-S Combination Sample BXFM-F + BXFM-ILHS + TR30-2 + U-KMAS + U-LH100L-3



* For installation dimensions, refer to those for the BXFM-F.

Weight: 5.5 kg (exclude objective lens)

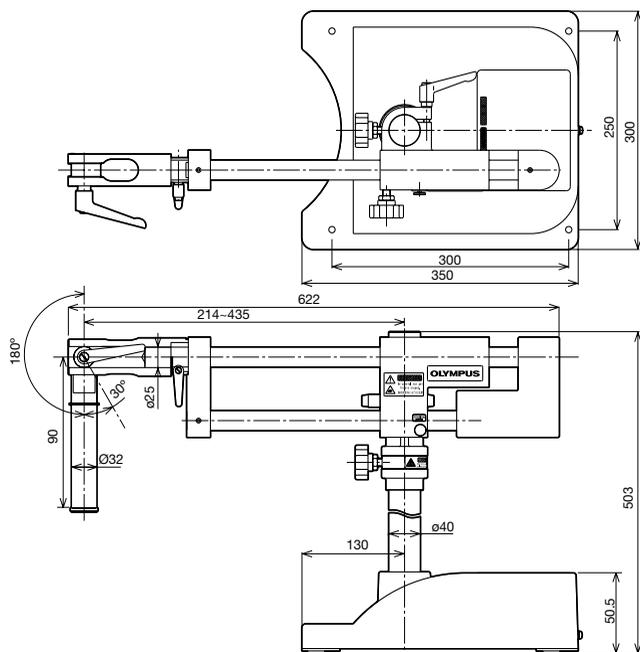
Unit: mm

Microscope System BXFM

Stands

A wide variety of stands are available to suit different applications and purposes.

SZ2-STU2
Universal Stand Type 2

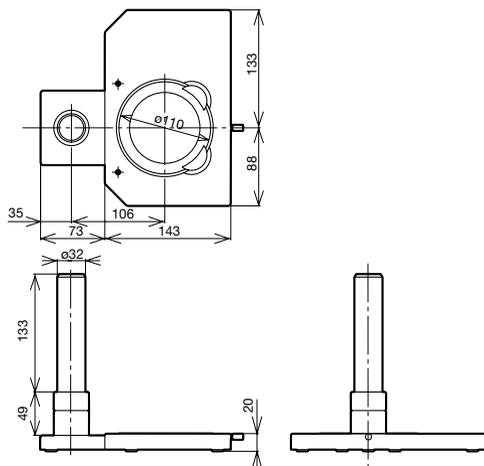


* The rotation angle of the horizontal arm can restrict to 90 degrees with stopper.

Major Specifications

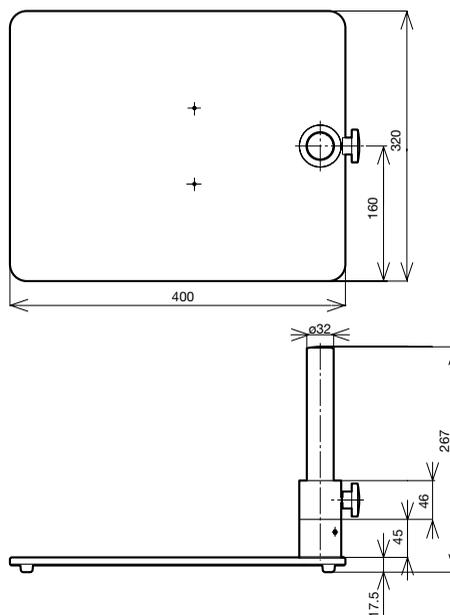
Item	Specifications
1 Diameter of Focusing Arm or Fixing Section of Tube	ø32 mm
2 Vertical Pole Diameter	ø40 mm
3 Horizontal Poles Diameters	ø25 mm (both upper and lower poles)
4 Stroke	Horizontal: 234 mm, Vertical: 205 mm
5 Movement Range	Horizontal: 541 (435+106) mm max. (vertical pole — BXFM-S optical axis)
6 Maximum Specimen Weight	Forward: 10 kg (within 90-degree area) Transverse Direction: 6 kg Backward Direction: 7 kg (at maximum stroke)
7 Weight	30 kg

U-ST
Compact Stand



Weight: 1.8 kg

SZ-STL
Large Stand



Weight: 5 kg

Unit: mm

Illumination Units

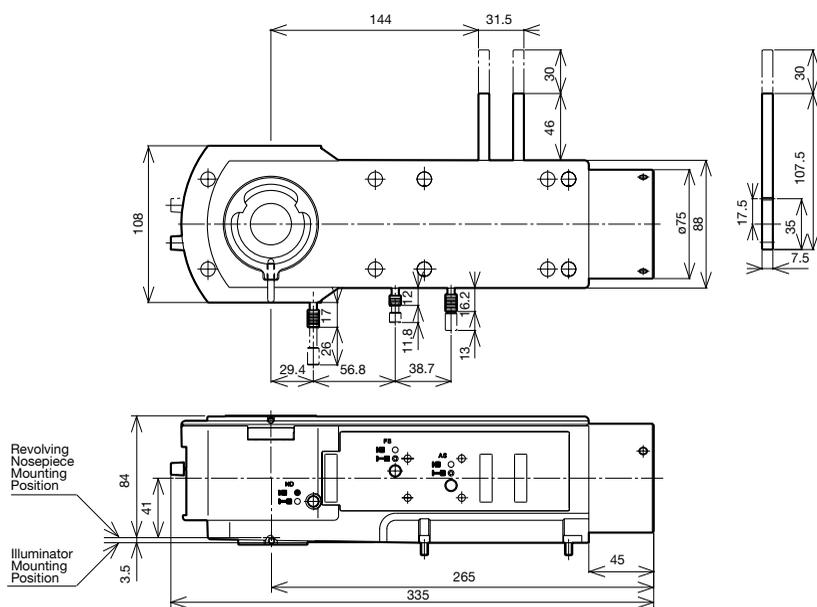
Reflected Light Illuminator for BF/DF

BX-RLA2

ND filters are linked when exchanging between brightfield and darkfield.

Accessories

Unit Name	Description	Weight (g)
U-25LBD	LBD Filter Slider	20
U-25IF550	IF550 Filter Slider	20
U-25ND6	ND Filter	20
U-25ND25	ND Filter	20
U-25FR	Frost Filter Slider	20
U-25L42	UV-cut Filter	20
U-PO3	Polarizer Slider for Reflected Light	71
U-POTP3	Polarizer Slider for Reflected Light with Tint Plate	71
U-AN360-3	360° Rotatable Analyzer Slider	79
U-AN	Analyzer Slider for Reflected Light	50
U-DICR	DIC Slider for Reflected Light	130
U-DICRH	DIC Slider for Reflected Light (high resolution type)	130
U-DICRHC	DIC Slider for Reflected Light (high contrast type)	130



Weight: 3.4 kg

Illumination Units

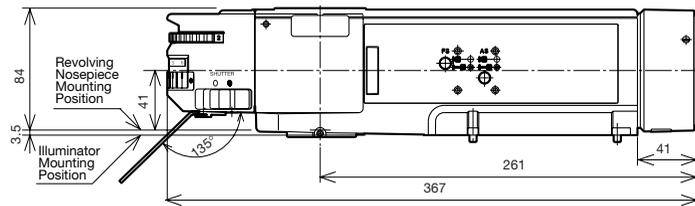
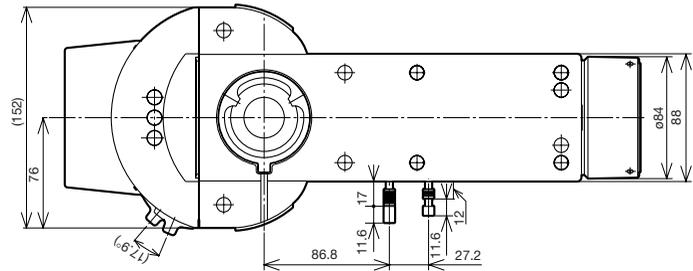
Universal Reflected Light Illuminator BX-URA2

Suitable for observations ranging from brightfield to fluorescence.

Six mirror units can be attached to this reflected light illuminator simultaneously.

Accessories

Unit Name	Description	Weight (g)
U-25LBD	LBD Filter Slider	20
U-25IF550	IF550 Filter Slider	20
U-25ND6	ND Filter	20
U-25ND25	ND Filter	20
U-25FR	Frost Filter Slider	20
U-25L42	UV-cut Filter	20
U-PO3	Polarizer Slider for Reflected Light	71
U-POTP3	Polarizer Slider for Reflected Light with Tint Plate	71
U-AN360-3	360° Rotatable Analyzer Slider	79
U-AN	Analyzer Slider for Reflected Light	50
U-DICR	DIC Slider for Reflected Light	130
U-DICRH	DIC Slider for Reflected Light (high resolution type)	130
U-DICRHC	DIC Slider for Reflected Light (high contrast type)	130
U-MBF3	Mirror Unit for Reflected Brightfield	80
U-MDF3*	Mirror Unit for Reflected Darkfield	80
U-MDIC3	Mirror Unit for Reflected DIC	80
U-MBFL3	Mirror Unit for Reflected Brightfield, for High Intensity Light Source	80
U-MWUS3	Fluorescence Mirror Unit for Reflected (U excitation)	80
U-MWBS3	Fluorescence Mirror Unit for Reflected (B excitation)	80
U-MWGS3	Fluorescence Mirror Unit for Reflected (G excitation)	80

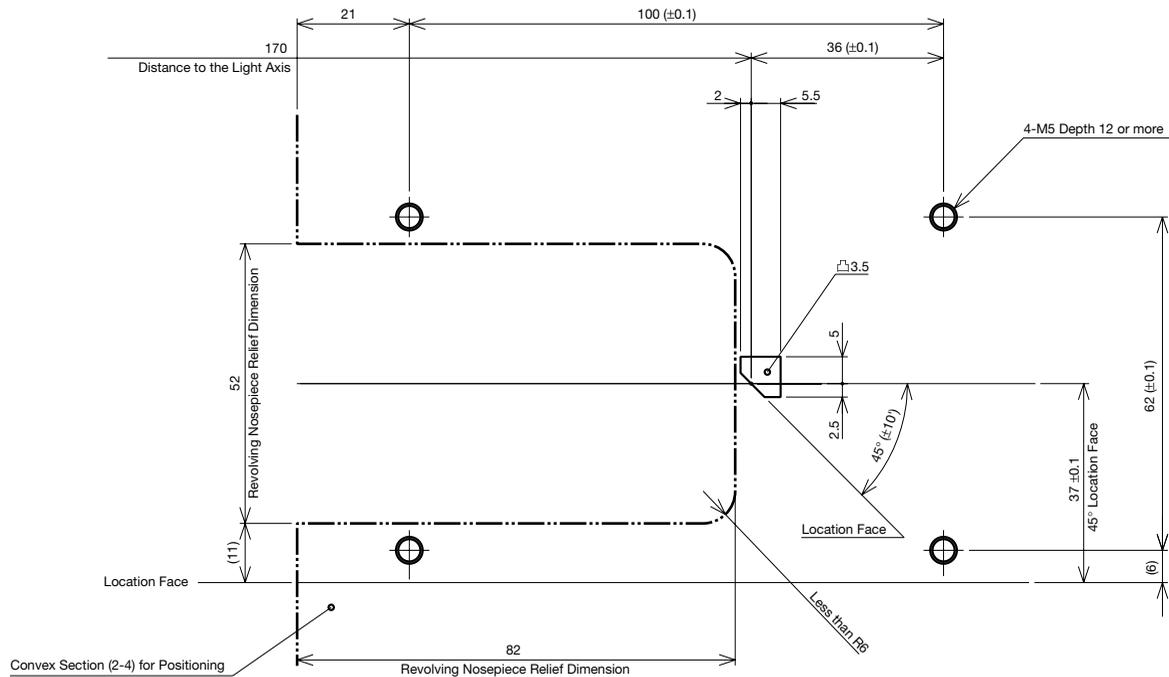


Weight: 3.8 kg

* U-RCV (DF converter for BX-URA2) is needed with darkfield observation.

Unit: mm

Mounting Dimensions of Illuminators (BX-RLA2 and BX-URA2)



Fix illuminator using four M5 screws and projection for fastening.

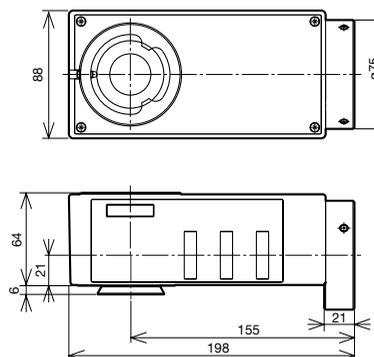
Unit: mm

Reflected Light Illuminator for BF U-KMAS

Very compact reflected light illuminator with reduced depth.

Accessories

Unit Name	Description	Weight (g)
U-25LBD	LBD Filter Slider	20
U-25IF550	IF550 Filter Slider	20
U-25ND6	ND Filter	20
U-25ND25	ND Filter	20
U-25FR	Frost Filter Slider	20
U-25L42	UV-cut Filter	20
U-PO3	Polarizer Slider for Reflected Light	71
U-POTP3	Polarizer Slider for Reflected Light with Tint Plate	71
U-AN360-3	360° Rotatable Analyzer Slider	79
U-AN	Analyzer Slider for Reflected Light	50
U-DICR	DIC Slider for Reflected Light	130
U-DICRH	DIC Slider for Reflected Light (high resolution type)	130
U-DICRHC	DIC Slider for Reflected Light (high contrast type)	130



Weight: 1.2 kg

Unit: mm

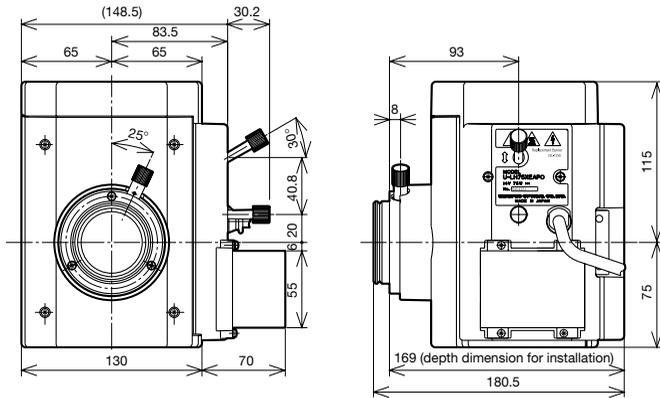
Light Source Units

Lamp Housings

Various different lamp housings are available, for use with different light sources: choose to suit the intended purpose.

* If you use the units in your production line, please consult your nearest Olympus representative in your region about the use conditions beforehand.

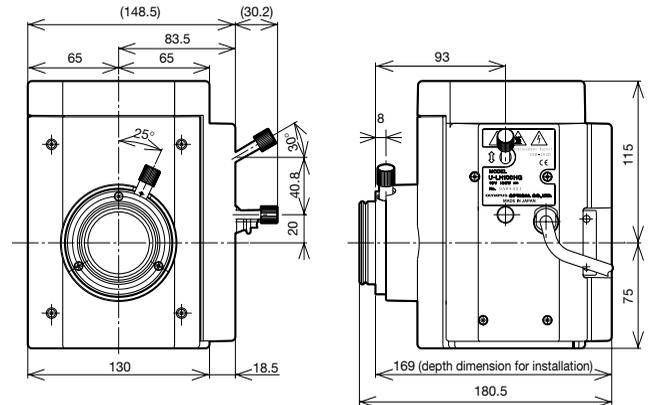
U-LH75XEAP0
75 W Xenon Apo Lamp Housing



Cable Length 2,000 mm Accepted Lamp: UXL-75XB Weight: 3.1 kg

*Power supply unit (U-RX-T) and power cable (UYCP) are necessary for 75 W xenon lamp housing. These items are sold separately.

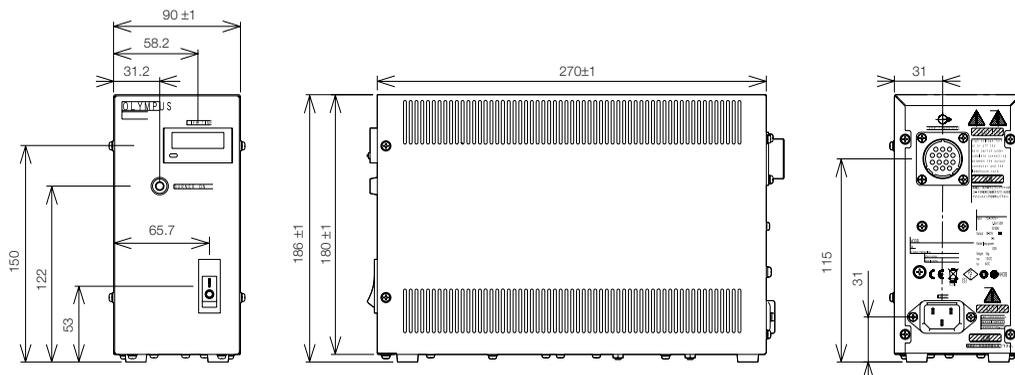
U-LH100HGAP0
100 W Mercury Apo Lamp Housing
U-LH100HG
100 W Mercury Lamp Housing



Cable Length 2,000 mm Accepted Lamp: USH-1030L Weight: 2.7 kg

* Power supply unit (U-RFL-T) and power cable (UYCP) are necessary for 100 W mercury lamp housings. These items are sold separately.

U-RX-T
Power Supply Unit for Xenon Lamp
U-RFL-T
Power Supply Unit for Mercury Lamp



Weight: Approximately 3 kg

Unit: mm

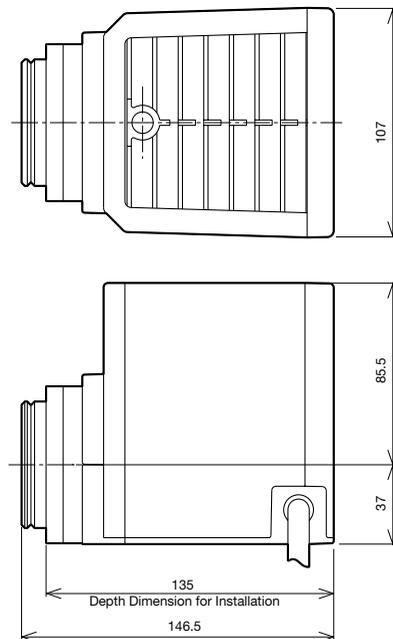
Light Source Units

Halogen Illumination

For the 100 W halogen lamp, the external power supply TH4-100/200 with an intensity adjustment switch and an ON/OFF switch, both are located close to the operator's hand, are provided.

* If you use the units in your production line, please consult your nearest Olympus representative in your region about the use conditions beforehand. *Illumination devices for microscope have suggested lifetimes. Periodic inspections are required. Please visit our web site for details.*

U-LH100-3/U-LH100IR/U-LH100L-3 100 W Halogen Lamp Housings



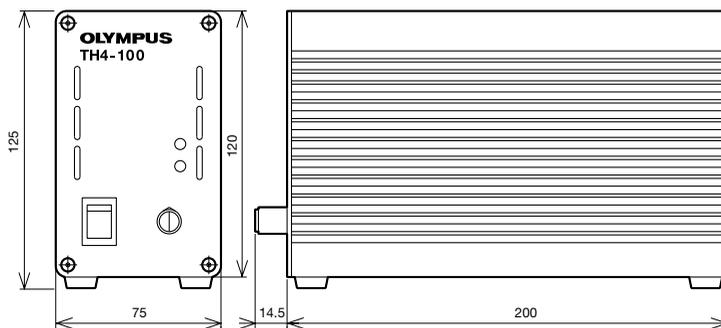
Cable Length U-LH100-3: 290 mm
U-LH100IR: 290 mm
U-LH100L-3: 800 mm

Accepted Lamp: 12V100WHAL (high intensity lamp)
12V100WHAL-L (long life lamp)

* External power supply (TH4-100 or TH4-200) and power cable (UYCP) are necessary for 100 W halogen lamp housings. These items are sold separately.

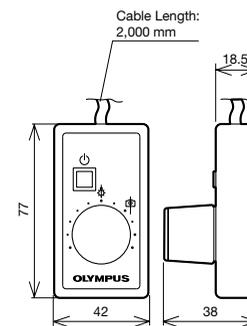
Weight: 880 g

TH4-100/200 External Power Supply



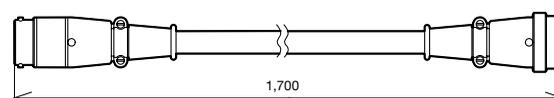
Weight: 2.2 kg

TH4-HS Hand Switch



Weight: 140 g

U-RMT Extension Cord



Weight: 200 g

Unit: mm

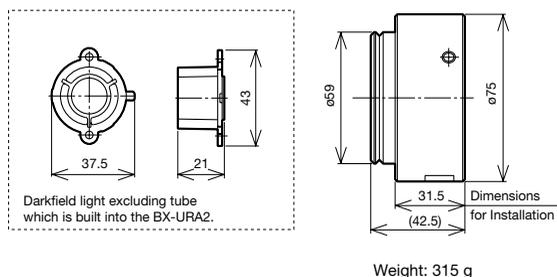
Light Source Units

Halogen Fiber Illumination Accessories

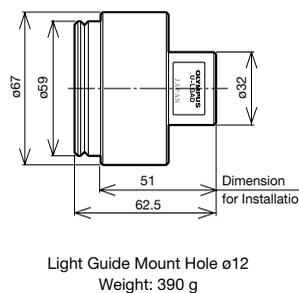
All Olympus reflected light illuminators can be used with fiber illumination.

* If you use the units in your production line, please consult your nearest Olympus representative in your region about the use conditions beforehand. *Illumination devices for microscope have suggested lifetimes. Periodic inspections are required. Please visit our web site for details.*

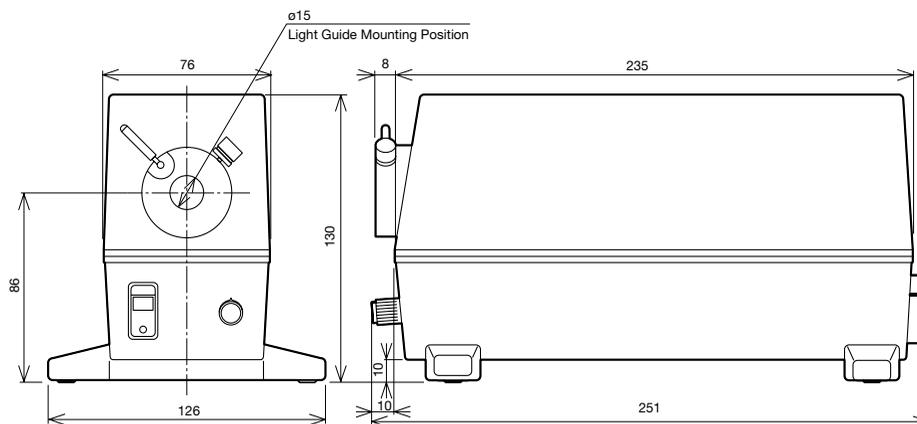
U-RCV
DF Converter for BX-URA2



U-LGAD
Fiber Adapter for Reflected Light Observation

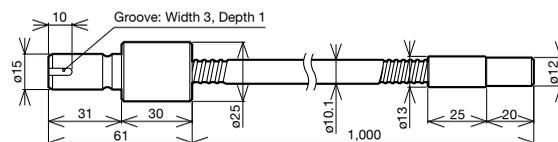


LG-PS2*
Light Source



*The types of model varies by country in use.

LG-SF
Light Guide



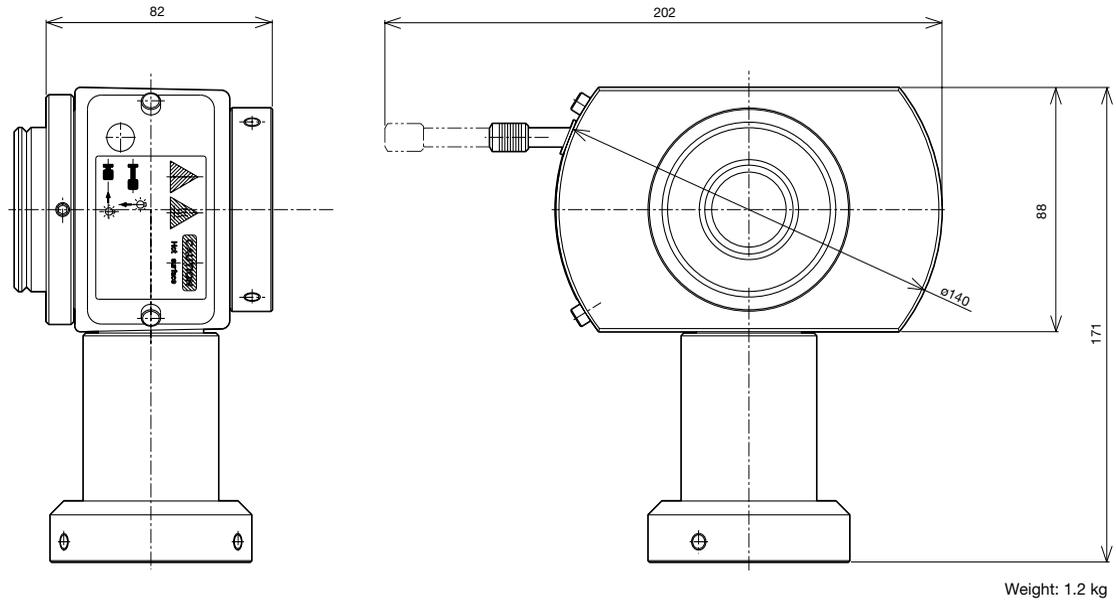
Unit: mm

Lamp Housing Accessory

Two lamp housings can be attached simultaneously.

* If you use the units in your production line, please consult your nearest Olympus representative in your region about the use conditions beforehand.

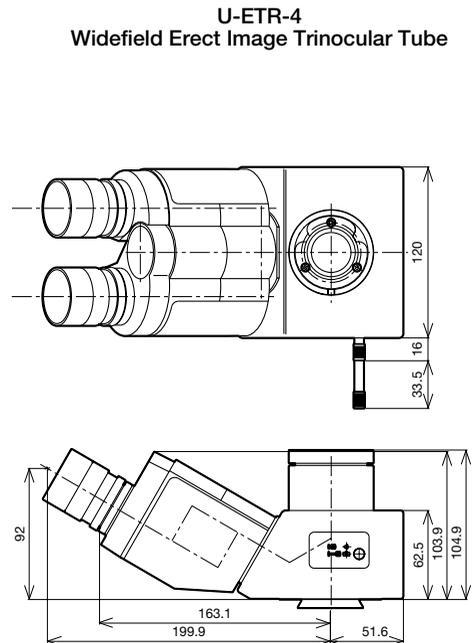
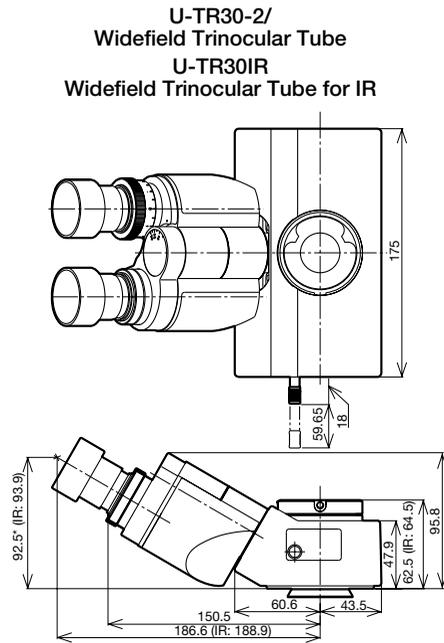
U-DULHA
Double Lamp House Adapter



Observation Tubes

Widefield Trinocular Observation Tubes

Trinocular observation tubes with widefield of view. Compatible with F.N. 22.



Unit: mm

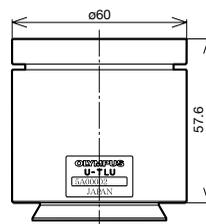
Name	Field Number (F.N.)	Inclination Angle (degree)	Interpupillary Distance (mm)	Light Path Selector (eyepiece/video port)	Observation Image	Weight (g)
U-TR30-2	22	30	50-76	100/0, 20/80, 0/100	Inverted	1600
U-TR30IR	22	30	50-76	100/0, 0/100	Inverted	1600
U-ETR-4	22	30	50-76	100/0, 0/100	Erect	1900

Length marked with an asterisk () may vary according to interpupillary distance. The distance for figure shown is 62 mm.

Single Port Tube with Lens

When the visual observation is not needed and only video observation is required, a single port tube with a built-in telan lens can be attached directly to the video port.

**U-TLU
Single Port Tube with Lens**
**U-TLUIR
Single Port Tube with Lens for IR**



Weight: 350 g

• For attachable video camera adapters, refer to video camera adapters system diagram page (pages 5-6).

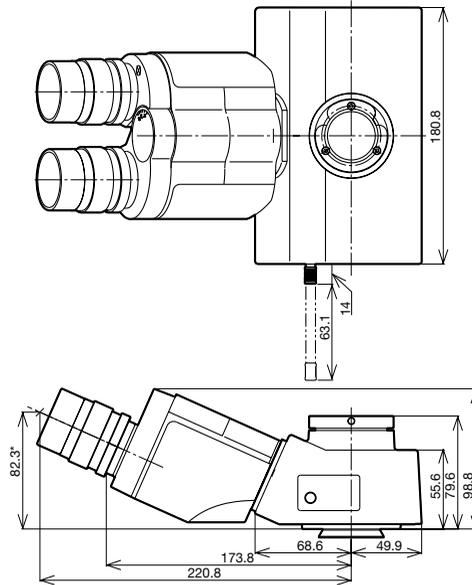
Unit: mm

Observation Tubes

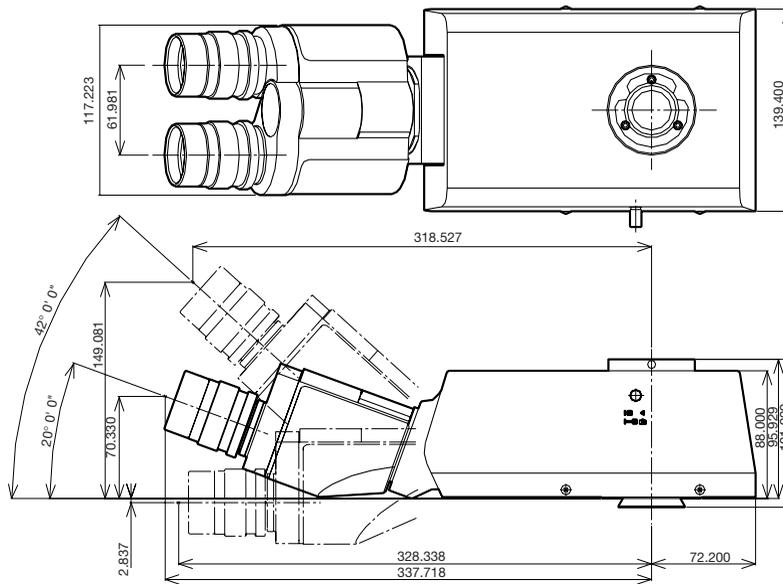
Super Widefield Trinocular Observation Tubes

Trinocular observation tubes with super widefield of view. Compatible with F.N. 26.5.

U-SWTR-3
Super Widefield Trinocular Tube



MX-SWETTR
Super Widefield Erect Image Tilting Trinocular Tube



Unit: mm

Name	Field Number (F.N.)	Inclination Angle (degree)	Interpupillary Distance (mm)	Light Path Selector (eyepiece/video port)	Observation Image	Weight (g)
U-SWTR-3	26.5	24	50-76	100/0, 20/80, 0/100	Inverted	2300
MX-SWETTR	26.5	0-42	50-76	100/0, 0/100	Erect	4200

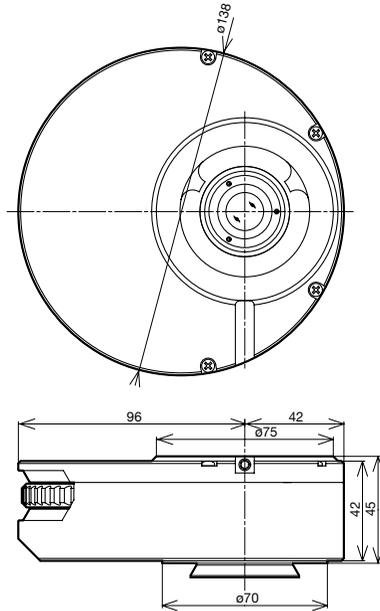
Length marked with an asterisk () may vary according to interpupillary distance. The distance for figure shown is 62 mm.

Intermediate Tubes

Various accessories for various observation need.

U-CA Magnification Changer

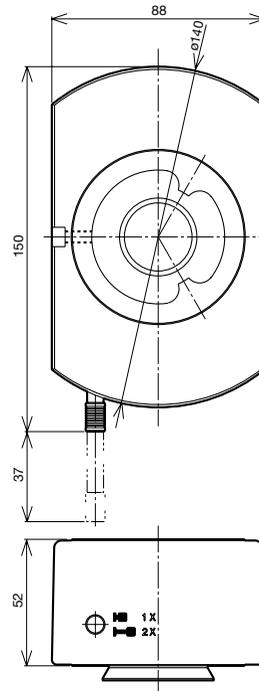
Provides 1x, 1.2x, 1.6x and 2x intermediate magnifications.



Weight: 1.3 kg

U-ECA Magnification Changer 2x

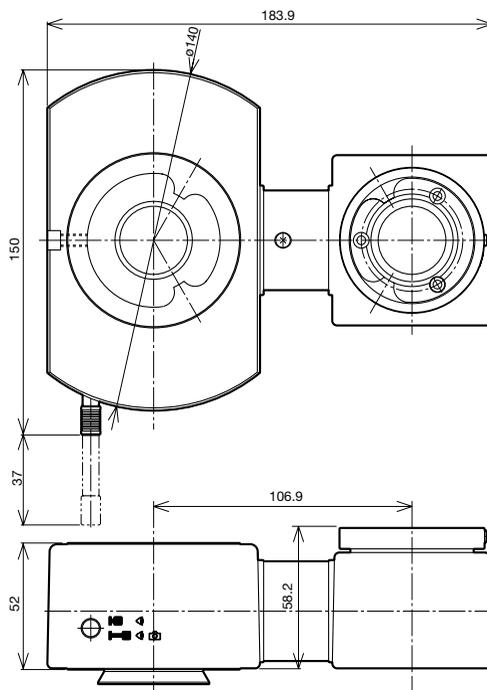
Provides 1x and 2x intermediate magnifications.



Weight: 1.3 kg

U-TRU Trinocular Intermediate Attachment

Intermediate attachment which divides the light path, allowing attachment of both digital and video cameras.



BI:PT=100:0/20:80

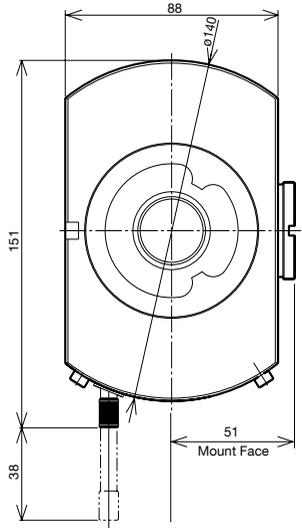
Weight: 1.3 kg

Unit: mm

Intermediate Tubes & Accessories

U-DP Dual Port

Use this intermediate tube to divide the light path.



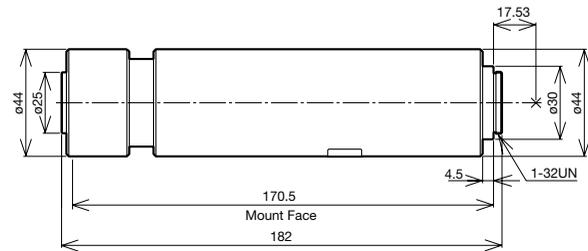
Weight: 1 kg

Light Path Selector by Mirror Unit

-  Transmitted Side Port: Side Port = 100:0
-  Transmitted Side Port: Side Port = 70:30 (with use of U-MBF3)

U-DP1xC Dual Port 1x

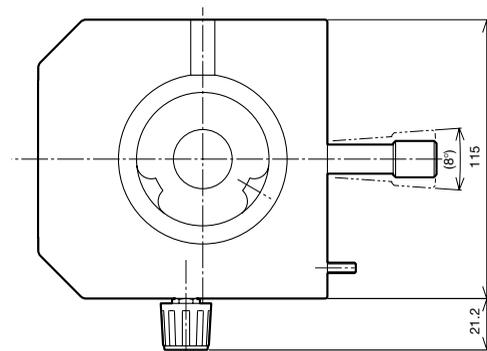
Combine with U-DP to obtain a 1x image.



Weight: 500 g

U-APT Arrow Pointer

Projects an arrow into the field of view.

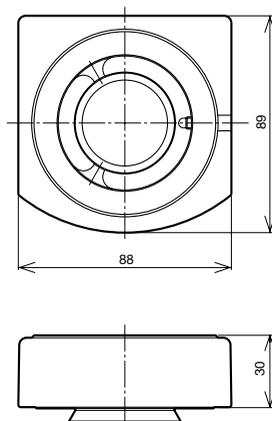


Weight: 1.2 kg

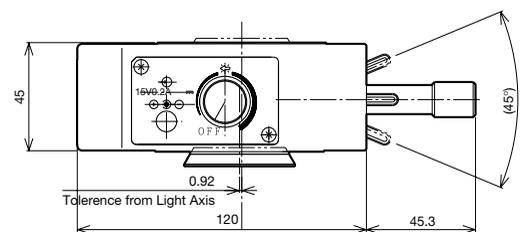
Unit: mm

U-EPA2 Eyepoint Adjuster

Raises eyepoint by 30 mm.



Weight: Approximately 500 g

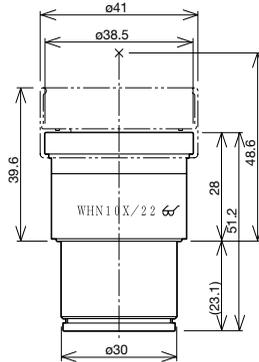


Eyepieces/Filar Micrometer Eyepiece

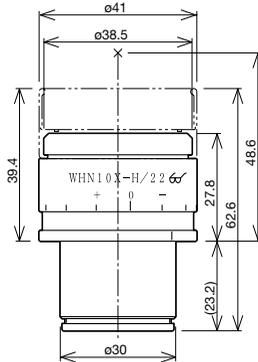
Eyepieces

Eyepieces for UIS2 optical system.

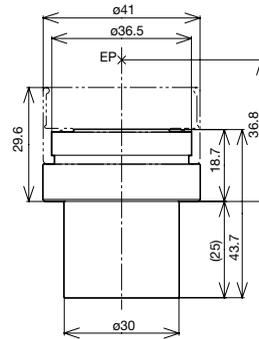
WHN10x
Widefield Eyepiece



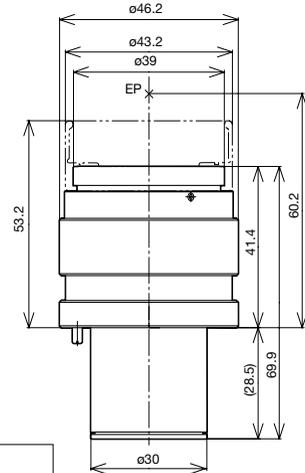
WHN10x-H
CROSSWHN10x
Widefield Eyepieces



WH15x
Widefield Eyepiece



SWH10x-H
MICROSSWH10x
CROSSWH10x
Super Widefield Eyepieces



Name	Field Number	Diopter Adjustment Range (1/m)	Micrometer Diameter (mm)	Weight (g)	Remarks
WHN10x	22	—	24	90	
WHN10x-H	22	-8 — +5	24	170	with Adjustable Diopter
CROSSWHN10x	22	-8 — +5	—	170	with Cross Lines and Adjustable Diopter
WH15x	14	—	24	90	
SWH10x-H	26.5	-8 — +2	—	210	with Adjustable Diopter
MICROSSWH10x	26.5	-8 — +2	—	210	with Micrometer and Adjustable Diopter
CROSSWH10x	26.5	-8 — +2	—	210	with Cross Lines and Adjustable Diopter

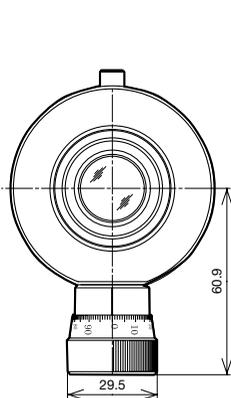
*EP=eyepoint

Unit: mm

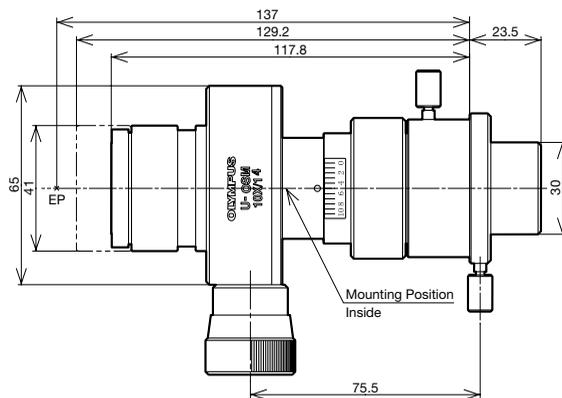
Filar Micrometer Eyepiece

U-OSM

Used for precise measurement in the field of view.



Weight: 580 g



Unit: mm

Eyepiece	Magnification 10x, Erect Image (inverted when used with erect image observation tube), F.N. 14. Diopter Adjustment Range: ±5 1/m. Provided with Rubber Eye Shade.
Measuring Scale	Scale Lines Graduated in Increments of 1 mm in the Entire 10 mm Length. Shift of Scale Lines: 1 mm per Rotation of the Sift Ring, the Circumference of Which is Divided into 100 Graduations.
Measuring Range	10 mm/Objective Lens Magnification
Compensation Limit for Objective Lens Magnification Tolerance	±5 % by Combined Use of the Zoom Compensation Ring and the Provided Stage Micrometer. Compensation Ring Clamping screw. Magnification Compensation Scale.
Actual Size	Actual Size (mm) = $\frac{\text{Measured Value (mm)}}{\text{Objective Lens Magnification}}$
Repeatability	Repeatability Error $\pm \frac{0.007}{A}$ mm (A ... Objective Lens Magnification)
Accuracy	*Measuring Error (A ... Objective Lens Magnification: L ... Measured Length in mm) $\pm [(0.0002 \times A + 0.002) L + \frac{0.007}{A}]$ mm

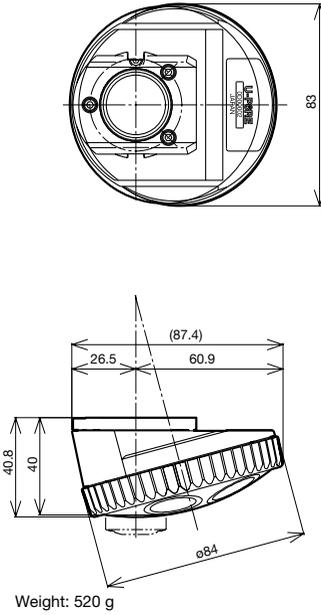
Revolving Nosepieces

Revolving Nosepieces for BF Objective Lenses

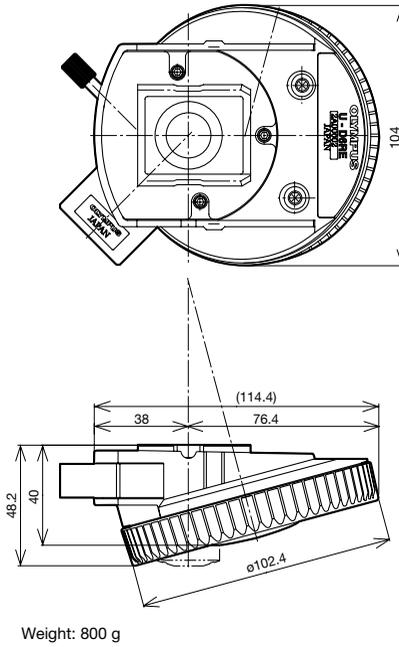
Choose from following 6 types. For motorized nosepieces, refer to motorized unit page.

Insert the DIC dummy when not using the DIC slider.

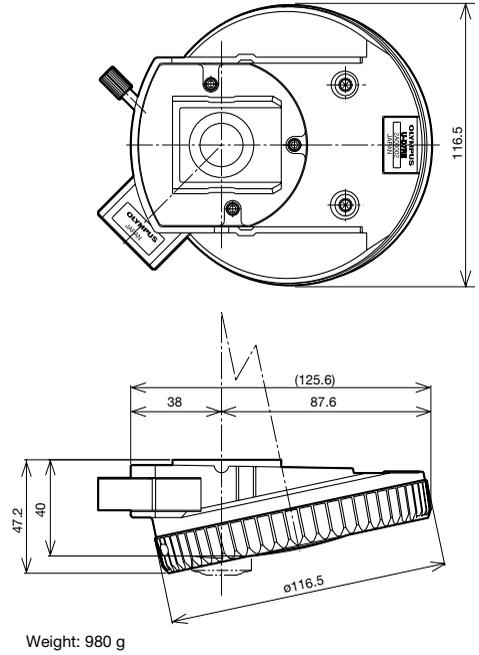
U-5RE-2
Quintuple Revolving Nosepiece



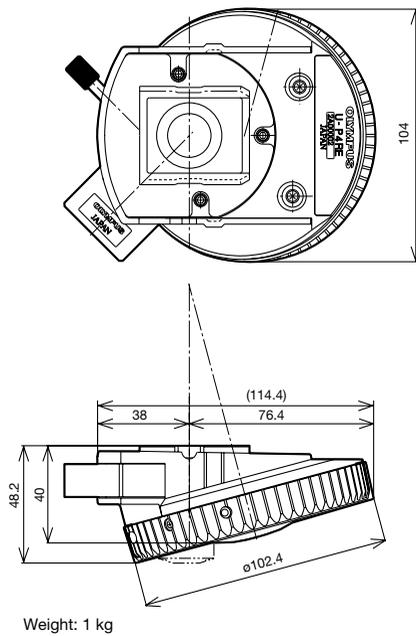
U-D6RE
Sextuple Revolving Nosepiece with Slider Slot for DIC
U-D6RE-ESD-2
Sextuple Revolving Nosepiece with Slider Slot for DIC
with ESD Treatment



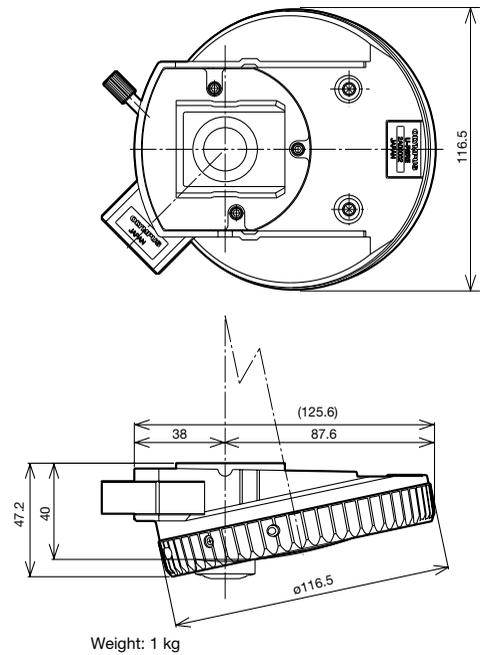
U-D7RE
Septuple Revolving Nosepiece with Slider Slot for DIC



U-P4RE
Centerable Quadruple Revolving Nosepiece with
Slider Slot for DIC



U-P6RE
Centerable Sextuple Revolving Nosepiece with
Slider Slot for DIC



Unit: mm

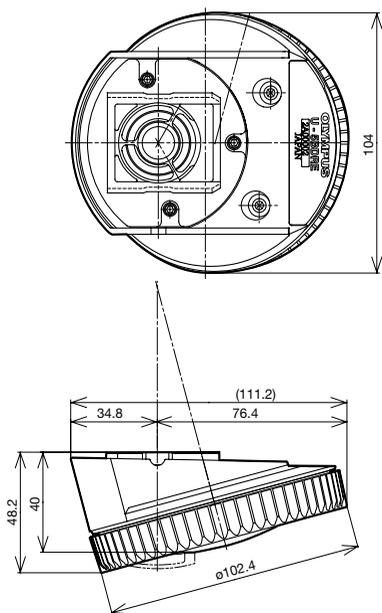
Revolving Nosepieces

Revolving Nosepieces for BF/DF Objective Lenses

Choose from following 3 types. Use of adapter to mount BF objectives (BD-M-AD) enables attachment of brightfield objective lenses. For motorized nosepieces, refer to motorized unit page.

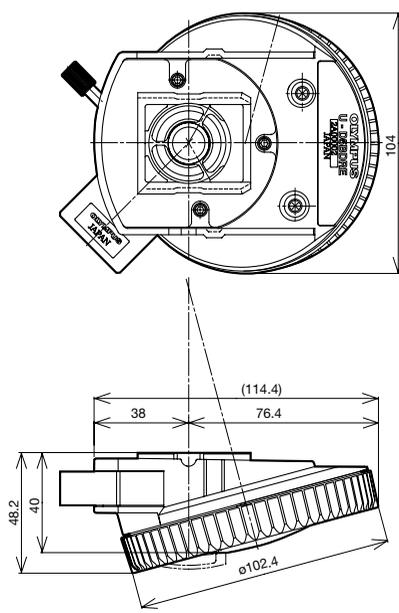
Insert the DIC dummy when not using the DIC slider.

U-5BDRE
Quintuple Revolving Nosepiece for BF/DF



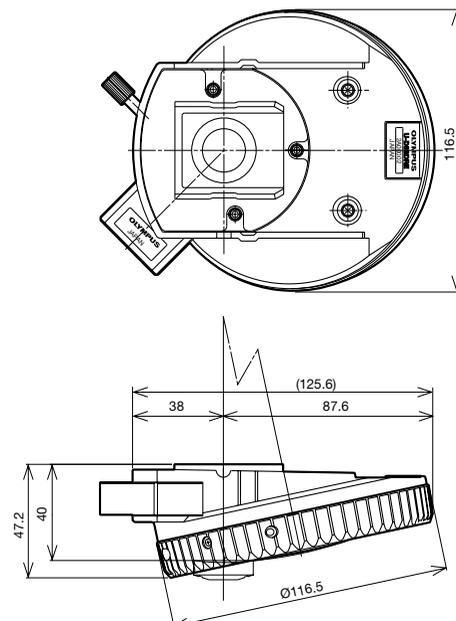
Weight: 800 g

U-D5BDRE
Quintuple Revolving Nosepiece for BF/DF with Slider Slot for DIC



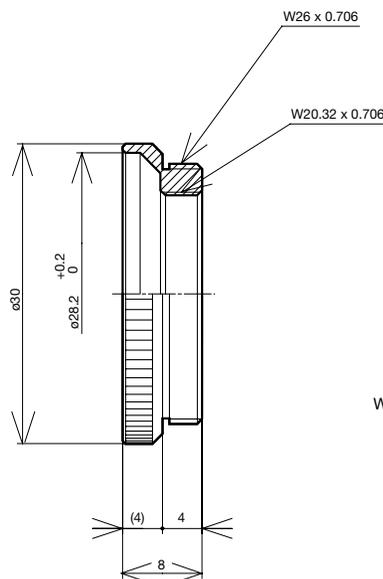
Weight: 800 g

U-D6BDRE
Sextuple Revolving Nosepiece for BF/DF with Slider Slot for DIC/
U-P5BDRE
Centerable Quintuple Revolving Nosepiece



Weight: 1 kg

BD-M-AD
Adapter to Mount BF Objectives



Weight: 10 g

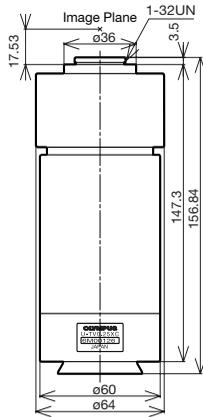
Unit: mm

Video Camera Adapters

C-mount Video Camera Ports

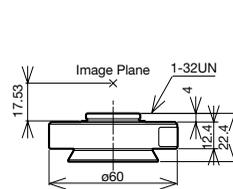
Allows direct attachment of a C-mount video camera. Five types are provided: 1x, 0.63x, 0.5x, 0.35x and 0.25x. All models feature a focus adjustment function.

U-TV0.25xC
C-mount Video Port with 0.25x Lens



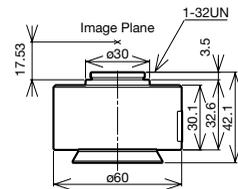
Weight: 1.2 kg

U-TV0.35xC-2
C-mount Video Port with 0.35x Lens



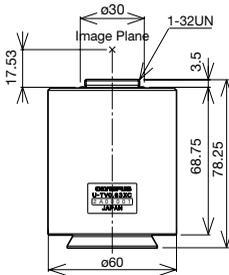
Weight: 100 g

U-TV0.5xC-3
C-mount Video Port with 0.5x Lens



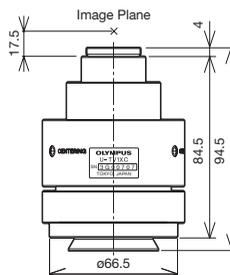
Weight: 200 g

U-TV0.63xC
C-mount Video Port with 0.63x Lens



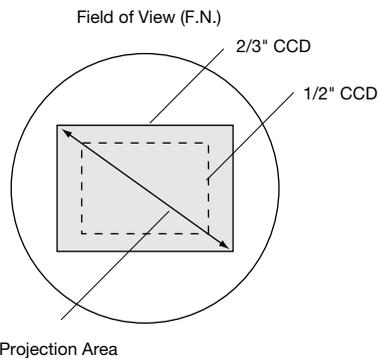
Weight: 430 g

U-TV1xC
C-mount Video Port with 1x Lens



Weight: 300 g

Unit: mm



Video Camera Adapter (projection lens)	Projection Magnifications	Projection Area (F.N.)		
		2/3" CCD	1/2" CCD	1/3" CCD
U-TV1x-2	1x	11	8	6
U-TV1xC	1x	11	8	6
U-TV0.63xC	0.63x	17.5	12.7	9.5
U-TV0.5xC-3	0.5x	22	16	12
U-TV0.35xC-2	0.35x	—	22	17.1
U-TV0.25xC	0.25x	—	—	24

$$\text{Practical Field of View (mm)} = \frac{\text{Projection Area (field number)}}{\text{Objective Lens Magnifications}}$$

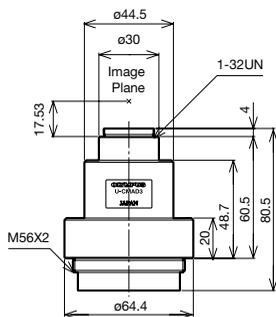
Focus the video camera adapter to prevent defocusing the eyepiece image and defocusing by magnification switching. Generally, the video camera adapter is focused by switching to a low magnification after focusing at a high magnification objective lens.

Video Camera Adapters

Video Camera Mount Adapters

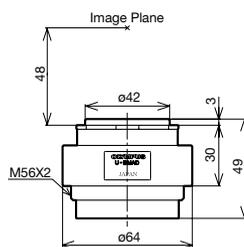
Allows attachment to video cameras with C, Bayonet, Sony and F mounts. Use with the U-TV1x-2. Focus by amount of screwing into U-TV1x-2.

U-CMAD3
C-mount Adapter



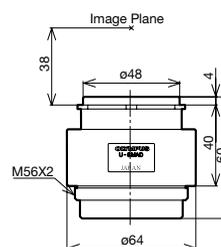
Weight: 165 g

U-BMAD
Bayonet Mount Adapter



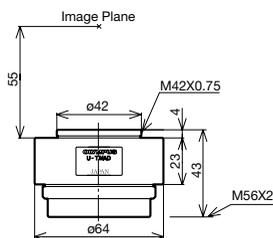
Weight: 80 g

U-SMAD
Sony Mount Adapter



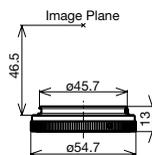
Weight: 90 g

U-TMAD
T Mount Adapter



Weight: 70 g

U-FMT
F/T Mount Adapter *



Weight: 30 g

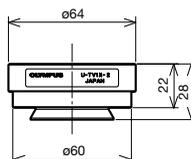
* It must be combined with U-TMAD.

Unit: mm

Video Camera Port

This port can be attached directly to the trinocular observation tube as well as to the single port tube with lens.

U-TV1x-2
Video Port 1x



Weight: 150 g

Unit: mm

Motorized Units

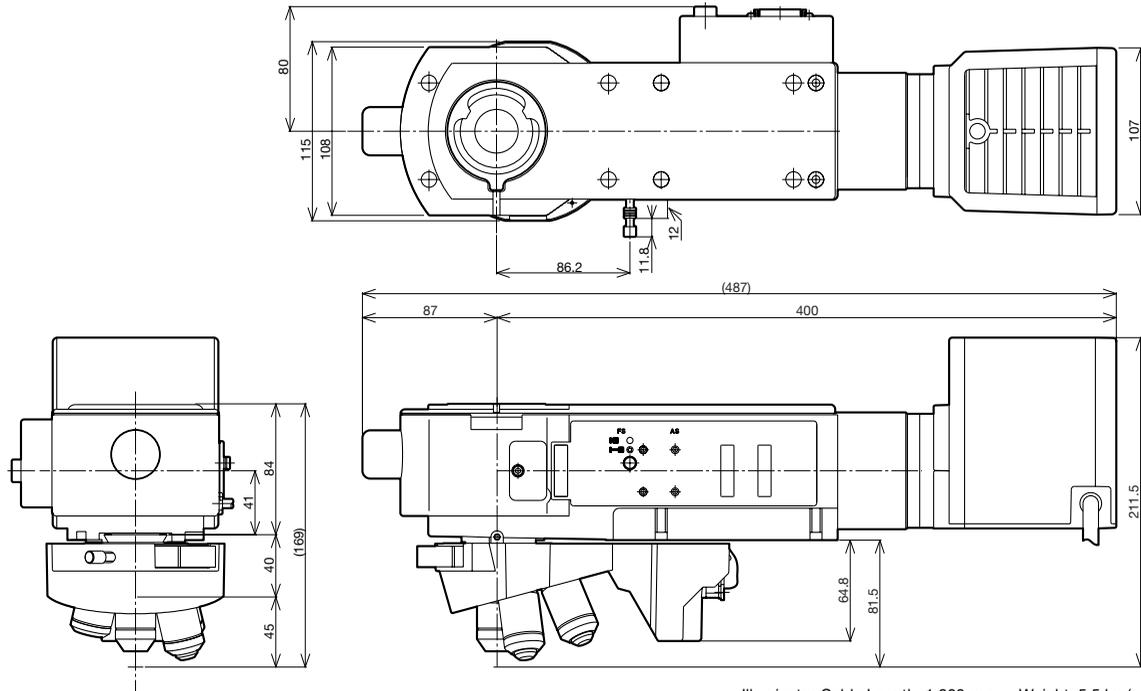
Motorized Units

Various motorized units, perfect for automation of equipment, are available.

BX-RLAA + U-D6REMC + U-LH100-3

Motorized BF/DF Reflected Light Illuminator + Motorized Nomarski DIC Sextuple Revolving Nosepiece + 100 W Halogen Lamp Housing

Enables motorized exchange of objective lenses, selection between brightfield and darkfield observations as well as aperture diaphragm closing/opening. The BX-UCB control unit has an RS232C connector, allowing control via a PC. For method of attaching illuminator, refer to page 24.

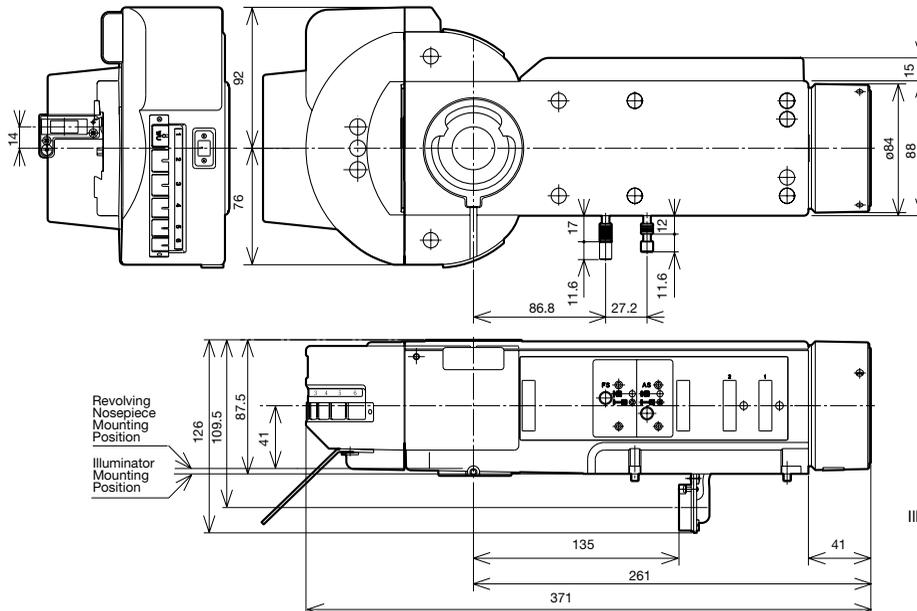


Illuminator Cable Length: 1.800 mm Weight: 5.5 kg (exclude objective lens)

BX-RFAA

Motorized Universal Reflected Light Illuminator

Reflected light fluorescence illuminator with simultaneous attachment of six mirror units. Incorporates motorized mirror unit changeover and shutter.



Illuminator Cable Length: 1.800 mm Weight: 4.3 kg

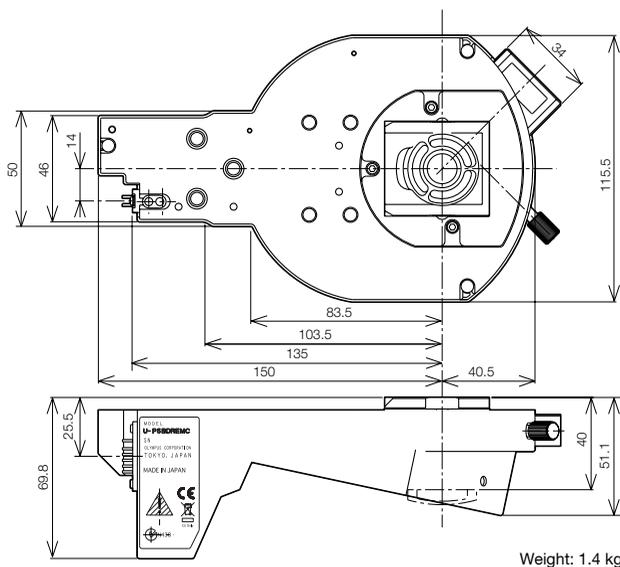
Unit: mm

Motorized Units

Motorized Units

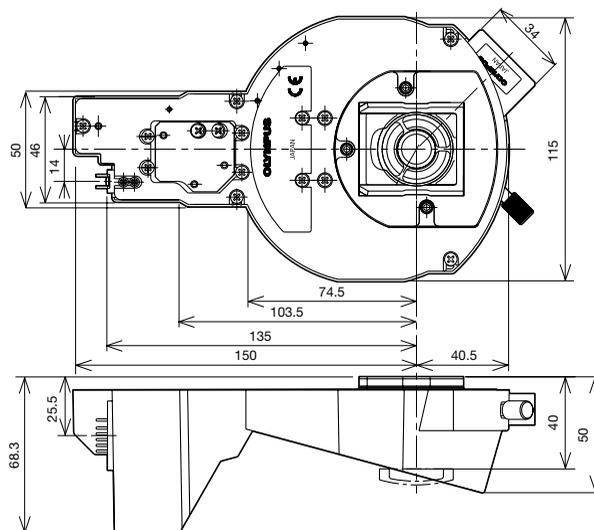
Various motorized units, perfect for automation of equipment, are available.

U-D6BDREMC
Motorized Sextuple BD Revolving Nosepiece with Slider Slot for DIC
U-P5BDREMC
Motorized Centerable Quintuple BD Revolving Nosepiece with Slider Slot for DIC



Weight: 1.4 kg

U-D5BDREMC
Motorized Quintuple BD Revolving Nosepiece with Slider Slot for DIC
U-D6REMC
Motorized Sextuple Revolving Nosepiece with Slider Slot for DIC
U-P5REMC*
Motorized Centerable Quintuple Revolving Nosepiece with Slider Slot for DIC



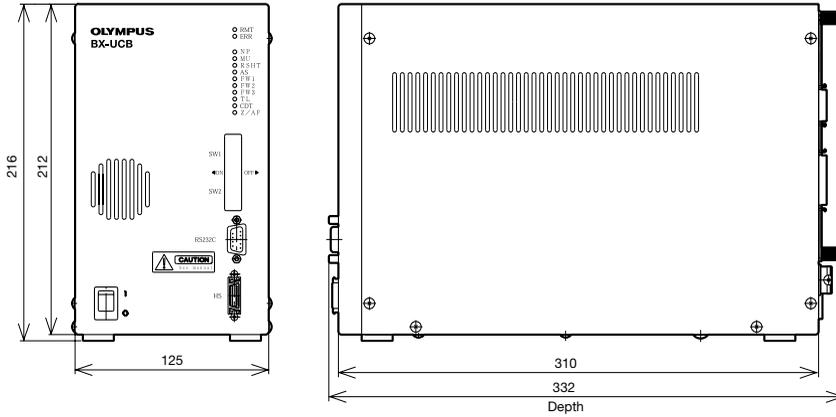
Unit: mm

*Please contact Olympus for the availability. Weight: 1.1 kg

Motorized Units

BX-UCB Control Unit

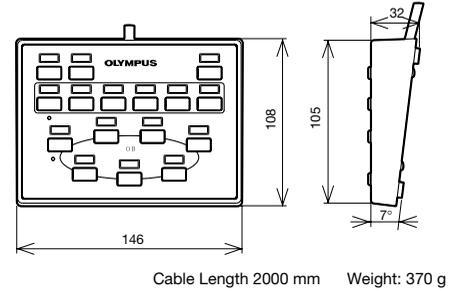
Motorized units including motorized illuminator and auto focus unit can be totally controlled from BX-UCB.



Weight: 1.0 kg

* Extension cord U-RMT (1700 mm) should be used to connect the lamp housing (U-LH100-3) to the BX-UCB.

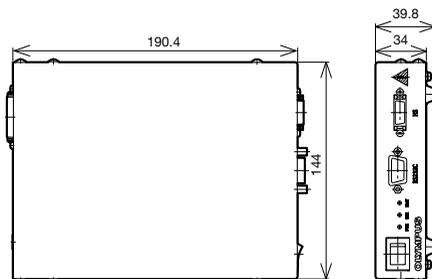
U-HSTR2 Hand Switch



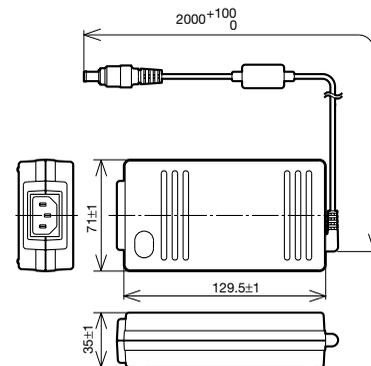
BX-REMCB Control Box for Motorized Nosepiece and BF/DF Illuminator

BX-RLAA and U-D5BDREMC/U-D6REMC/U-P5REMC can be controlled from U-HSTR2, or direct from the computer keyboard via an RS232C connector.

* BX-RFAA and U-D5BDREMC/U-D6REMC combination not applicable.



U-ACAD4515 AC Adapter for BX-REMCB



Unit: mm

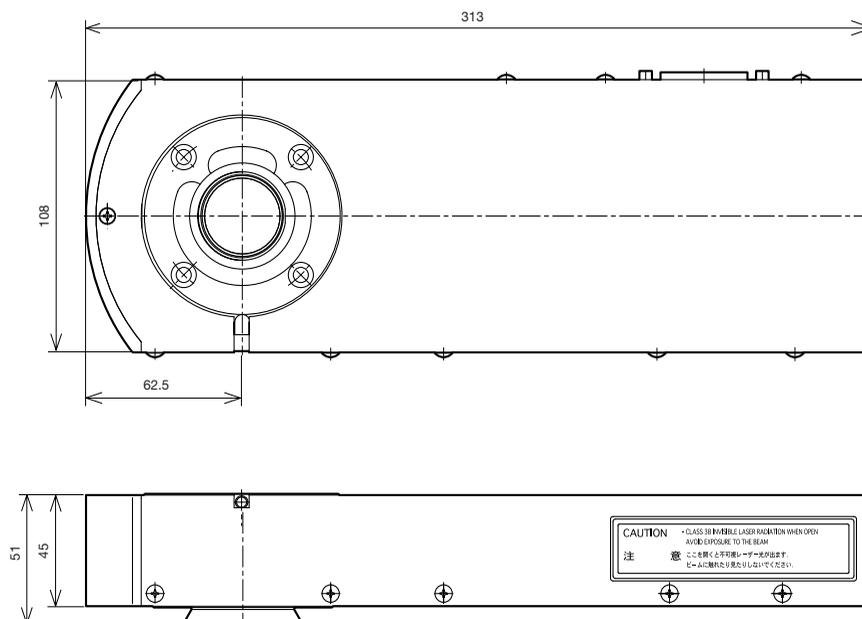
Motorized Units

Various motorized units, perfect for automation of equipment, are available.

U-AFA2M-VIS Active Auto Focus Unit

Featuring an AF laser light source in wavelength 785 nm. The multiple-spots sensor enables the high-speed and stable focusing of specimens with variable height differences

*Class 1 laser product



Weight: 2.6 kg

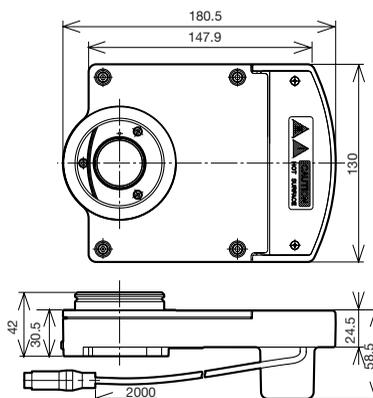
Cable

AFA2M-CBL2M Weight: 0.23 kg Length: 2 m
AFA2M-CBL3M Weight: 0.36 kg Length: 3 m

* Consult your Olympus dealer about the motorized focus.

U-FWR Motorized Reflected Filter Wheel

Accomplish maximum 6 filter position exchange.



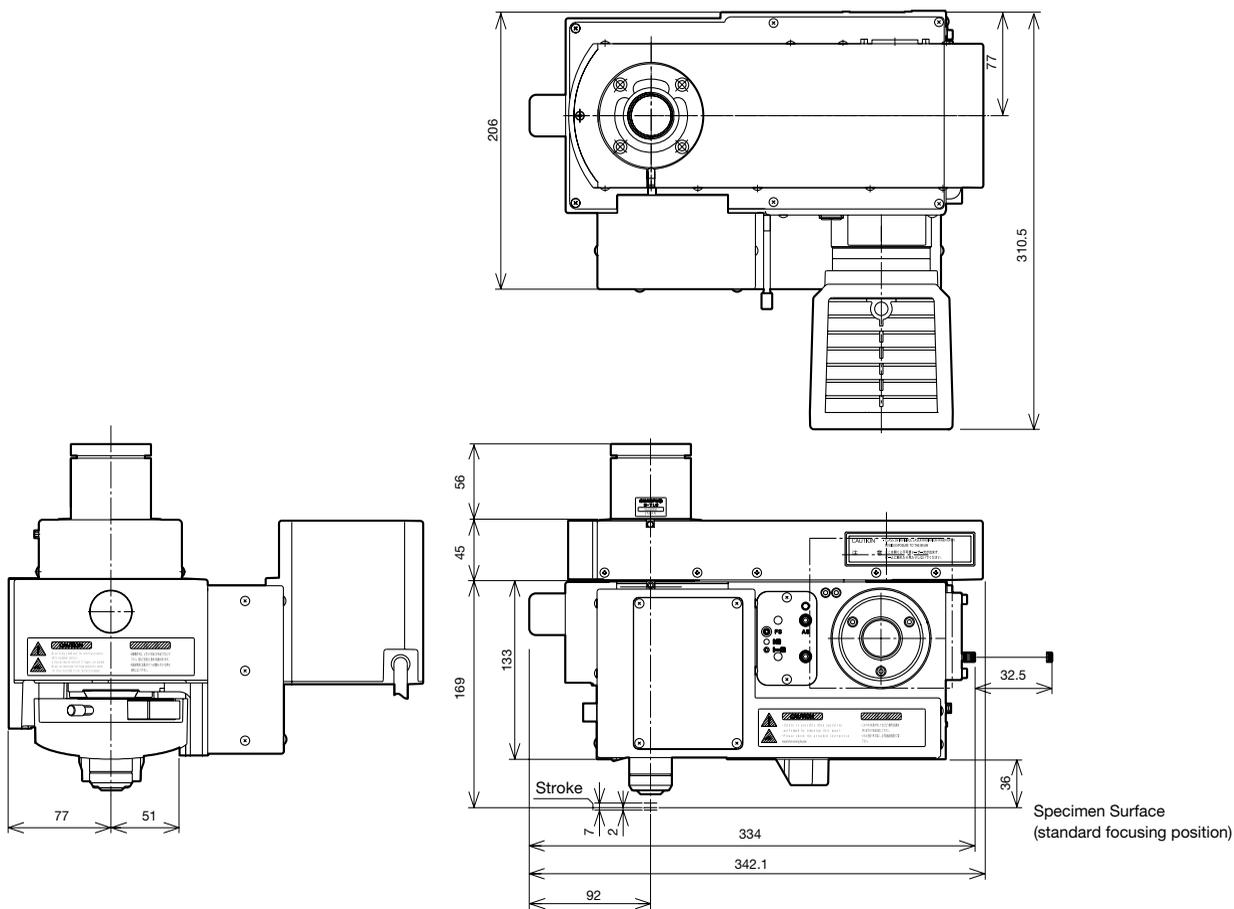
Weight: 1.0 kg

Unit: mm

Motorized Units

BXFMA-F Motorized Illumination with Power Focus

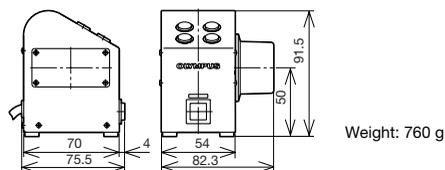
A motorized microscope unit for integration with your equipment. Motorized operations such as revolving nosepiece up/down, objective lens switching, aperture diaphragm open/close, and brightfield/darkfield switching are accomplished with this component. Several microscopic operations are totally controlled from an external unit by combining this component with an auto focus unit. This is the configuration combined with Active Auto Focus Unit U-AFA2M-VIS, Single Port Tube with Lens U-TLU, a lamp housing, a motorized nosepiece and objective lenses.



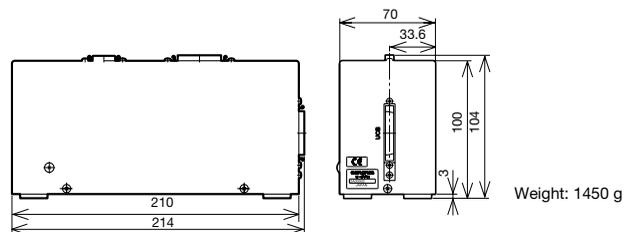
* Consult your Olympus dealer about the mounting dimensions.

Weight: 13 kg
(BXFMA-F frame 7.6 kg)

U-FH Focus Adjustment Knob Unit



U-IFFH Focus Adjustment Knob Interface



Unit: mm

Optical Terminology

1. Field Number (F.N.) and Practical Field of View

The field number (F.N.) is referred to as the diaphragm size of eyepiece in mm unit which defines the image area of specimen. The diaphragm diameter actually seen through eyepiece is known as the practical field of view (F.O.V.) which is determined by the formula:

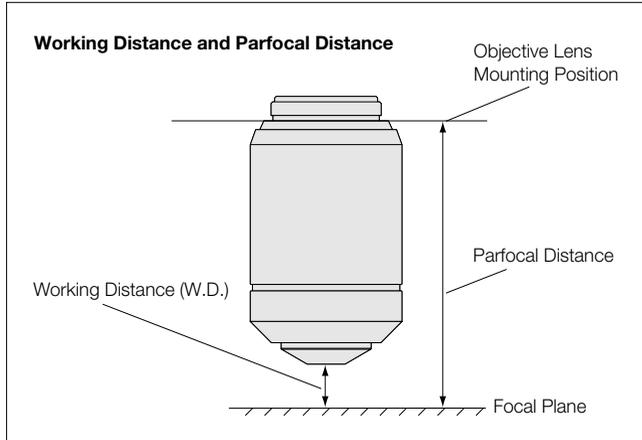
$$\text{F.O.V.} = \frac{\text{Eyepiece F.N.}}{\text{Objective Lens Magnification}} \text{ (mm)}$$

2. Working Distance (W.D.)

The distance between the front edge of the objective lens and the specimen surface (with the surface of the cover glass in case of the cover glass objective lens) when the specimen is focused.

3. Parfocal Distance

It is the distance between the objective lens mounting plane and the specimen. In UIS2/UIS objective lenses, the parfocal distance is designed at 45 mm.



For parfocal distance of the LCPLFLN-LCD series objective lenses, refer to the appropriate objective lens page.

4. Relationship Between the Objective Lens's Focal Length and Magnifications

Indicated magnifications of UIS2/UIS objective lenses are the values when the focal length of the tube lens is 180 mm.

$$M_{(ob)} = \frac{\text{Focal Length of Tube Lens}}{f}$$

$M_{(ob)}$: Objective Lens Magnification
 f : Objective Lens's Focal Length

5. Total Magnification

5.1 Observation Through Eyepiece (binocular observation)

$$M_{(bino)} = M_{(ob)} \times M_{(oc)}$$

$M_{(bino)}$: Total magnification for binocular observation

$M_{(ob)}$: Objective lens magnification

$M_{(oc)}$: Eyepiece magnification

5.2 Video Monitor Observation

● Total Magnification for Video Monitor

$$M_{(video\ monitor)} = M_{(ob)} \times M_{(video\ camera\ adapter)} \times \text{Monitor Magnification}^*$$

$M_{(video\ monitor)}$: Total Magnification on the Video Monitor

$M_{(ob)}$: Objective Lens Magnification

$M_{(video\ camera\ adapter)}$: Projected Magnification for Video Camera Adapter Including Photo Eyepiece
(refer to Figure 1)

* Refer to Figure 3 for "Monitor Magnification"

● Practical Field of View for Video Monitor Observation

$$\text{Practical Field of View for Video Monitor Observation} = \frac{\text{Image Device Size}^*}{M_{(ob)} \times M_{(video\ camera\ adapter)}}$$

$M_{(ob)}$: Objective Lens Magnification

$M_{(video\ camera\ adapter)}$: Projected Magnification for Video Camera Adapter Including Photo Eyepiece
(refer to Figure 1 for projected magnifications)

* Refer to Figure 2 for Image Device Size

Figure 1 Video Camera Adapter and Projection Magnifications

Video Camera Adapter (projection lens)	Projection Magnifications
U-TV1x-1 + Video Camera Mount Adapters	1x
U-TV1xC	1x
U-TV0.63xC	0.63x
U-TV0.5xC-3	0.5x
U-TV0.35xC-2	0.35x
U-TV0.25xC	0.25x

Figure 2 Imaging Device Size

Camera Format	Diagonal	Horizontal	Vertical
1/3"	6.0 mm	4.8 mm	3.6 mm
1/2"	8.0 mm	6.4 mm	4.8 mm
2/3"	11.0 mm	8.8 mm	6.6 mm

The above table is for standard image device sizes. Check your device size for precise calculation.

Figure 3 Imaging Device Size and Monitor Magnifications

Camera Format	Monitor Size (diagonal)				
	10"	15"	17"	19"	21"
1/3"	42.3x	63.5x	72.0x	80.4x	88.9x
1/2"	31.8x	47.6x	54.0x	60.3x	66.7x
2/3"	23.1x	34.6x	39.3x	43.9x	48.5x

Optical Terminology

Example

What is total magnifications for video monitor when objective lens is 50x, video camera adapter U-TV0.5xC, 2/3" video camera and 21" monitor are used ?

- Total magnification on the video monitor:

$M_{(ob)}=50\times$, $M_{(video\ camera\ adapter)}$ is 0.5x from Figure 1 and monitor magnification is 48.5x from Figure 3.

$$M_{(monitor\ observation)}=M_{(ob)}\times M_{(video\ camera\ adapter)}\times\text{monitor magnification}$$

$$=50\times 0.5\times 48.5=1213\times$$

- Practical field of view for video observation (horizontal side):

$M_{(ob)}=50\times$, $M_{(video\ camera\ adapter)}$ is 0.5x from Figure 1 and horizontal side of 2/3" imaging device is 8.8mm from Figure 2

$$\text{Practical Field of View for Video Observation} = \frac{\text{Image Device Size}}{M_{(ob)} \times M_{(video\ camera\ adapter)}}$$

$$= \frac{8.8\text{ (mm)}}{50 \times 0.5} = 352\ \mu\text{m}$$

6. Numerical Aperture (N.A.)

The numerical aperture is a key factor to the performance of objective lens (resolving power, focal depth and brightness).

The N.A. is determined by the following formula:

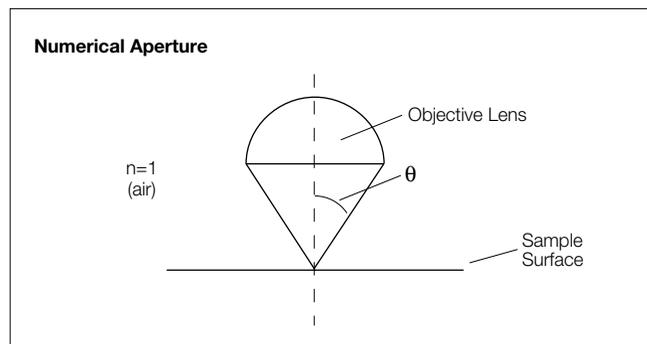
$$N.A. = n \times \sin\theta$$

n=Refraction Rate of the Medium between Specimen and Objective Lenses. (Air: n=1, oil: n=1.515)

θ : Angle Which is Made by the Optical Axis and Refraction of the Light Farthest from the Center of the Lens.

The visual field brightness (B) of the microscope is determined by the following formula in relation to the objective lens magnification (M). The larger the N.A. and the lower the objective magnification, brightness will increase in the factor of the second power.

$$B \propto \frac{N.A.^2}{M^2}$$



7. Resolving Power

The resolving power of an objective lens is measured by its ability to differentiate two lines or points in an object. The greater the resolving power, the smaller the minimum distance between two lines or points that can still be distinguished. The larger the N.A., the higher the resolving power.

● Resolving Power Formula

The following formula is generally used for determining resolution.

$$\epsilon = 0.61 \times \frac{\lambda}{N.A.} \text{ (Reyleigh formula)}$$

λ : Wavelength or Radiation in Use

($\lambda=0.55\ \mu\text{m}$ is used for visible light.)

N.A.: Objective Lens N.A.

Example

MPLFLN100x(N.A.=0.90), $\lambda=0.55\ \mu\text{m}$

$$\epsilon = 0.61 \times \frac{\lambda}{N.A.} = \frac{0.3355}{N.A.} = \frac{0.3355}{0.90} = 0.37\ \mu\text{m}$$

8. Focal Depth of Microscope

The focal depth refers to the depth of the specimen layer which is in sharp focus at the same time, even if the distance between the objective lens and the specimen plane is changed when observing and shooting the specimen plane by microscope. As human eyes are individually different in the ability of their focus adjustment, each person's perception of the focal depth varies. At present, the Berek formula is generally used, because it gives a focal depth value that often coincides with that obtained through experiments.

Focal Depth formula

- Visual Observation (Berek formula)

$$\pm D.O.F. = \frac{\omega \times 250,000}{N.A. \times M} + \frac{\lambda}{2(N.A.)^2} (\mu\text{m})$$

D.O.F.: Depth Of Focus

ω : Resolving Power of Eyes 0.0014
(when optical angle is 0.5 degrees)

M: Total Magnification
(objective lens magnification x eyepiece magnification)

$$\rightarrow \pm D.O.F. = \frac{350}{N.A. \times M} + \frac{0.275}{N.A.^2} (\lambda=0.55\ \mu\text{m})$$

This indicates that the focal depth becomes smaller as the numerical aperture becomes larger.

Example

With MPLFLN100x (N.A.=0.90), WHN10x:

$$\pm D.O.F. = \frac{350}{0.90 \times 1,000} + \frac{0.275}{0.81} = 0.39 + 0.34 = 0.73\ \mu\text{m}$$

Optical Terminology

● Video Camera

In the case of a video camera, the focal depth will vary according to number of pixels of CCD, optical magnification, and numerical aperture. The above-mentioned formula is used as a rough guide only.

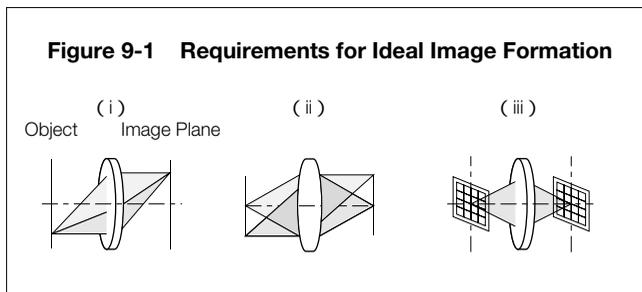
9. Aberrations

A difference between an ideal image and an actual image that passes through an optical system is called an “aberration.”

9.1 Requirements for Ideal Image Formation

The following three requirements must be satisfied to form an image with no aberration, or an ideal image.

- (i) All the light rays coming from a single point and passing through an image formation optical system converge on a single point.
- (ii) Image points, which correspond to object points on the same plane perpendicular to the optical axis, are present on the same plane.
- (iii) The planar shape of an object and the planar shape of an image that are on the same plane perpendicular to the optical axis have a similarity relation.

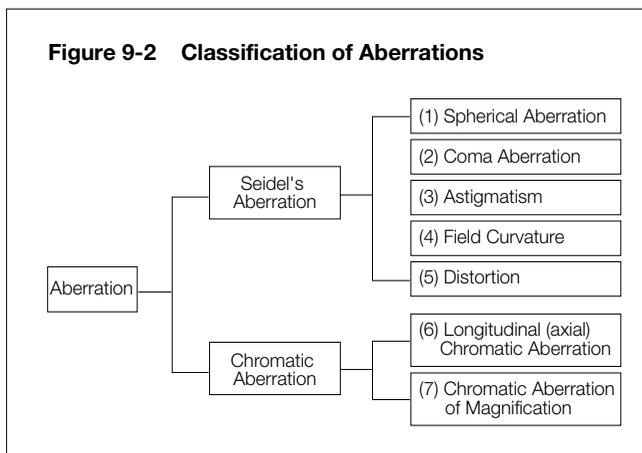


In an actual optical system, however, it is very difficult to strictly meet the requirements for ideal image formation and this causes “aberrations” that interfere with image forming performance.

9.2 Classification of Aberrations

Aberrations that interfere with image forming performance are classified as shown below in Figure 9-2.

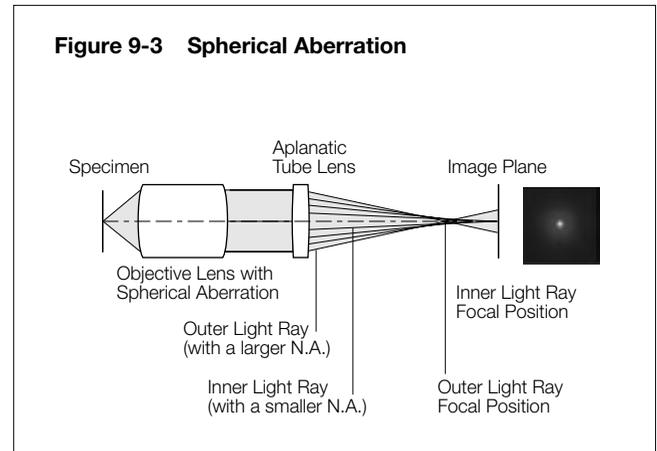
Seidel’s Aberration = “Expansion of a Point Image” + “Curvature of Image Plane” + “Deformation”



Types (1) to (3) correspond to “expansion of a point image” that goes against requirement (i) for ideal image formation in Figure 9-1. Type (4) corresponds to “curvature of image plane” that goes against requirement (ii) in Figure 9-1. Type (5) corresponds to “deformation” that goes against requirement (iii) in Figure 9-1. Types (6) and (7) correspond to “color blur” of images caused by characteristics of glass materials used for the optical system. “Expansion of a point image” can also be expressed by “wavefront aberration” that regards the light as “waves” and takes account of the phase to include the influence of diffraction.

(1) Spherical Aberration

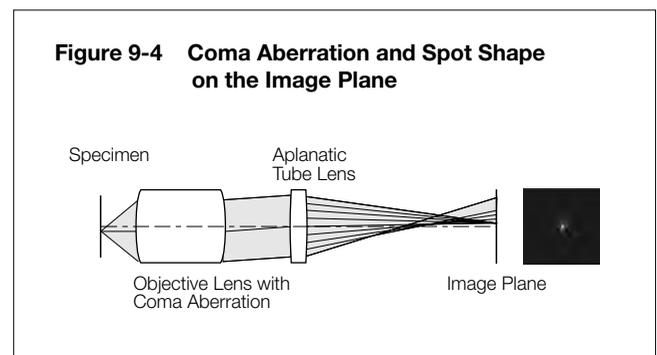
When light rays coming out of an axial object point enter a lens, the light rays with a larger numerical aperture (N.A.) are subjected to stronger refraction power and cross the optical axis in positions with larger differences from the ideal image formation position. The aberration caused this way by different image forming positions due to differences in N.A. of axial light rays is called “spherical aberration.” (“Spherical aberration” is proportional to the cube of N.A.)



It is said that objective lenses with larger N.A. have better resolution but worsen spherical aberration. Our advanced design and manufacturing techniques have realized good optical performance even with large numerical aperture.

(2) Coma Aberration

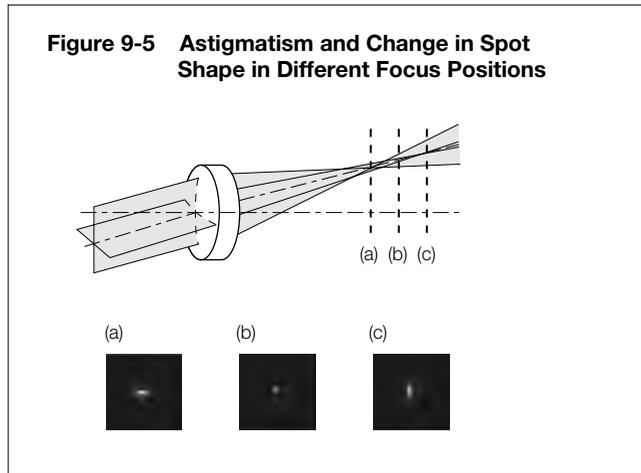
Even though spherical aberration is compensated to be very small, there are cases where light rays coming out of an off-axis object point are not condensed to a single point on the image plane but generate asymmetric blur just like a comet leaving traces. This is called coma aberration.



Optical Terminology

(3) Astigmatism

Even though a lens is compensated for spherical aberration and coma aberration, there are cases where an image of an off-axis object point is not focused to a single point but separated to a concentric line image and a radial line image. This is called "astigmatism." When astigmatism is present, a point image blurs vertically and horizontally, before and after the focus position.



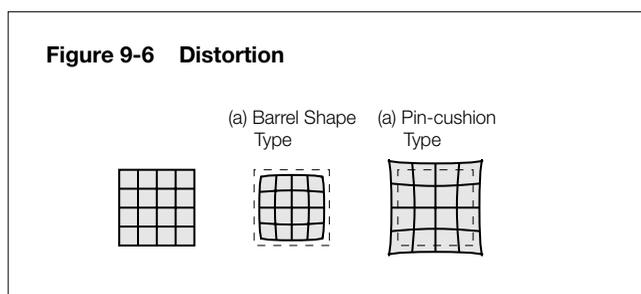
(4) Field Curvature

An image plane of an object on a plane perpendicular to an optical axis does not always become a plane perpendicular to the optical axis, but it generally becomes a curved plane. This symptom is called "field curvature."

When field curvature is present, the image is more displaced as it becomes closer to the periphery of the visual field. Therefore, when the center of an image is brought into focus, blur occurs in the peripheral areas of the image. To bring the entire image, including the periphery, into clear focus, it is necessary to adequately compensate for this type of aberration.

(5) Distortion

When there is no similar relation between a planar shape on an object and a shape on the image plane, this is called "distortion." When distortion is present, a square image appears in a shape of a barrel or pin-cushion as shown in Figure 9-6.



The microscope optical system contains some distortion. When distortion is present, it can bring erroneous results of shape measurements. When a microscope is used for precision measurements, pay close attention to this aberration, for example, by providing it with an aberration compensation function.

(6) Chromatic Aberration

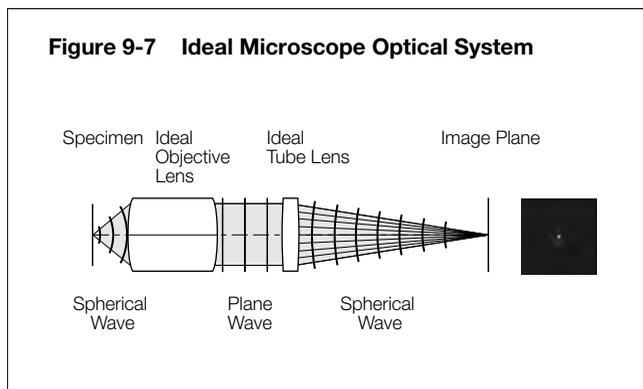
Glasses used for optical systems have different refractive indexes depending on the wavelength. This causes differences in focal length between wavelengths and generates displacement of image forming position. This phenomenon is called "chromatic aberration," which is sometimes subdivided into axial displacement on the optical axis, called "axial chromatic aberration" (or lateral chromatic aberration) and displacement on the image plane, called "chromatic aberration of magnitude."

Many special glass materials are used, e.g., for apochromats, to eliminate chromatic aberration in a wide range from violet light (g-rays with wavelength of 435 nm) to red light (c-rays with wavelength of 656 nm).

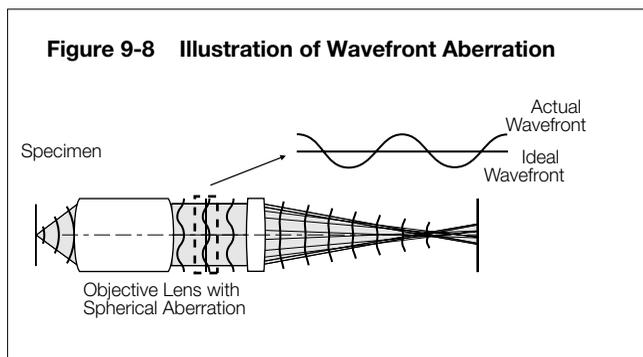
Optical Terminology

9.3 Wavefront Aberration

Since a long time ago, aberrations have been used in “geometric optics,” which considers light as “light rays.” Microscope optical systems are often used for observation of very small specimens at a wavelength level, and sometimes adopt “wave optics,” which regards light as “waves” and handles the phase information, taking account of the influence of diffraction. In such a case, “wavefront aberration” is used for evaluation. As shown below, when requirements for ideal imaging are satisfied in a microscope optical system, the spherical wavefront (spherical waves) coming from a single point on an object (specimen) is converted to plane waves through an ideal objective lens. The plane waves are converted to spherical waves through an ideal tube lens, and condensed to a single point. The wavefront of these waves is called the “ideal wavefront.”



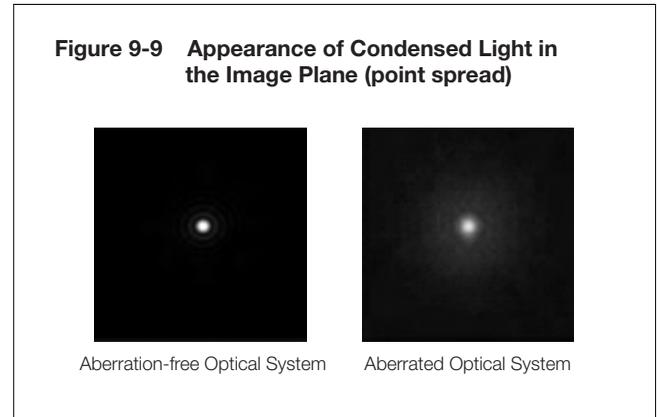
Based on the figure indicated for (1) spherical aberration, the behavior of the wavefront in an optical system that has an aberration is described below.



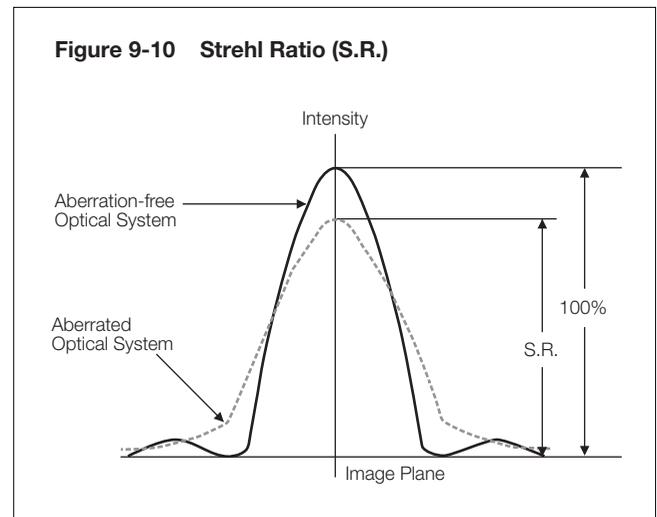
A difference (a degree of disagreement) between the ideal wavefront and the actual wavefront shown above is called “wavefront aberration.”

9.4 Strehl Ratio

When a point light source is observed with an aberration-free optical system and an aberrated optical system, the former concentrates the focal point to a point at the image formation position. In contrast, the latter fails to produce a focal point, instead causing a spread in the intensity distribution of the point image (this is known as “point spread”). The specific appearance of such a point image (i.e. point spread) is shown in Figure 9-9.



With the proportion of light concentrated in the image plane (intensity of light concentrated in the Airy disk) by an aberration-free optical system serving as 100%, the proportion of light concentrated by an aberrated optical system is known as the Strehl ratio. When graphed, the Strehl ratio reveals peaks in intensity as shown in Figure 9-10. The higher the S.R., the closer an optical system is to being aberration-free.



A Strehl ratio of 80% is typically called the diffraction limit, and lenses with a lower ratio lack the performance required to serve as an objective lens. A ratio of over 95% means that the lens’ performance in general observations is comparable to that of an aplanatic lens (which is corrected for spherical aberrations and coma).

Note: A laser interferometer is used for actual assessment of optical performance, so assessment is done at a single wavelength. Unless otherwise noted, Strehl ratio measurements are at the e-line (544 nm).

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